



**EDS – Energy Dispersive Spectrometry –  
Energo-disperzná röntgenová spektrometria**

**WDS – Wave Dispersive Spectrometry –  
Vlnovo-disperzná röntgenová spektrometria**

**Alica Rosová, IEE SAV Bratislava**

Recommended literature:

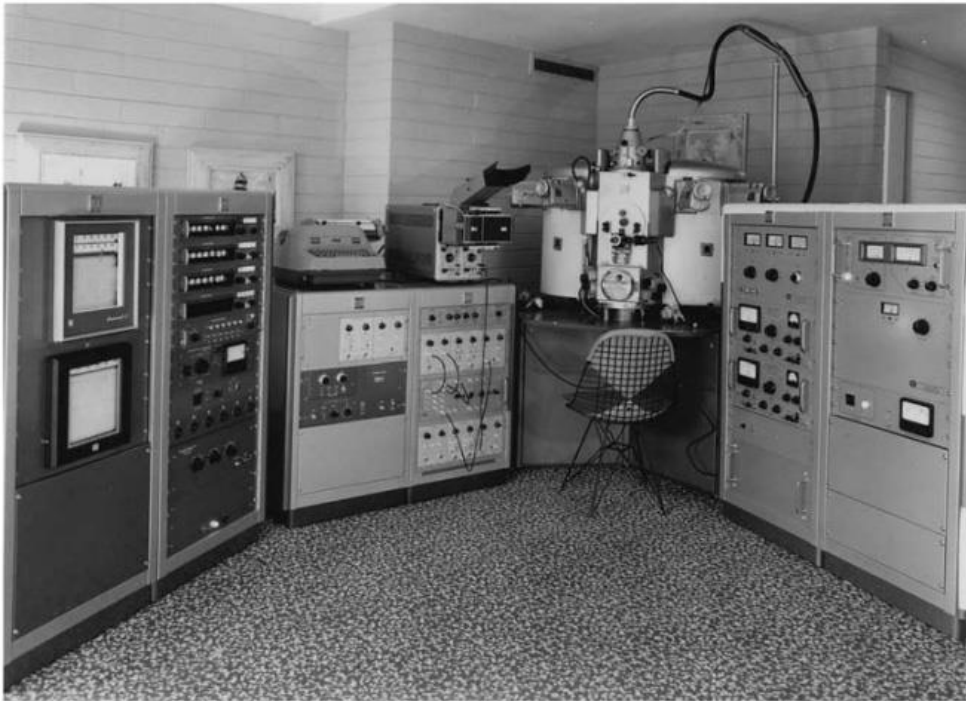
J.I. Goldstein et al: Scanning Electron Microscopy and  
X-Ray Microanalysis

CASINO: D. Druin, Sanning **29** (2007) 92-101.

and <http://www.gel.usherbrooke.ca/casino/index.html>

# EDS – EDX - EDAX versus EPMA

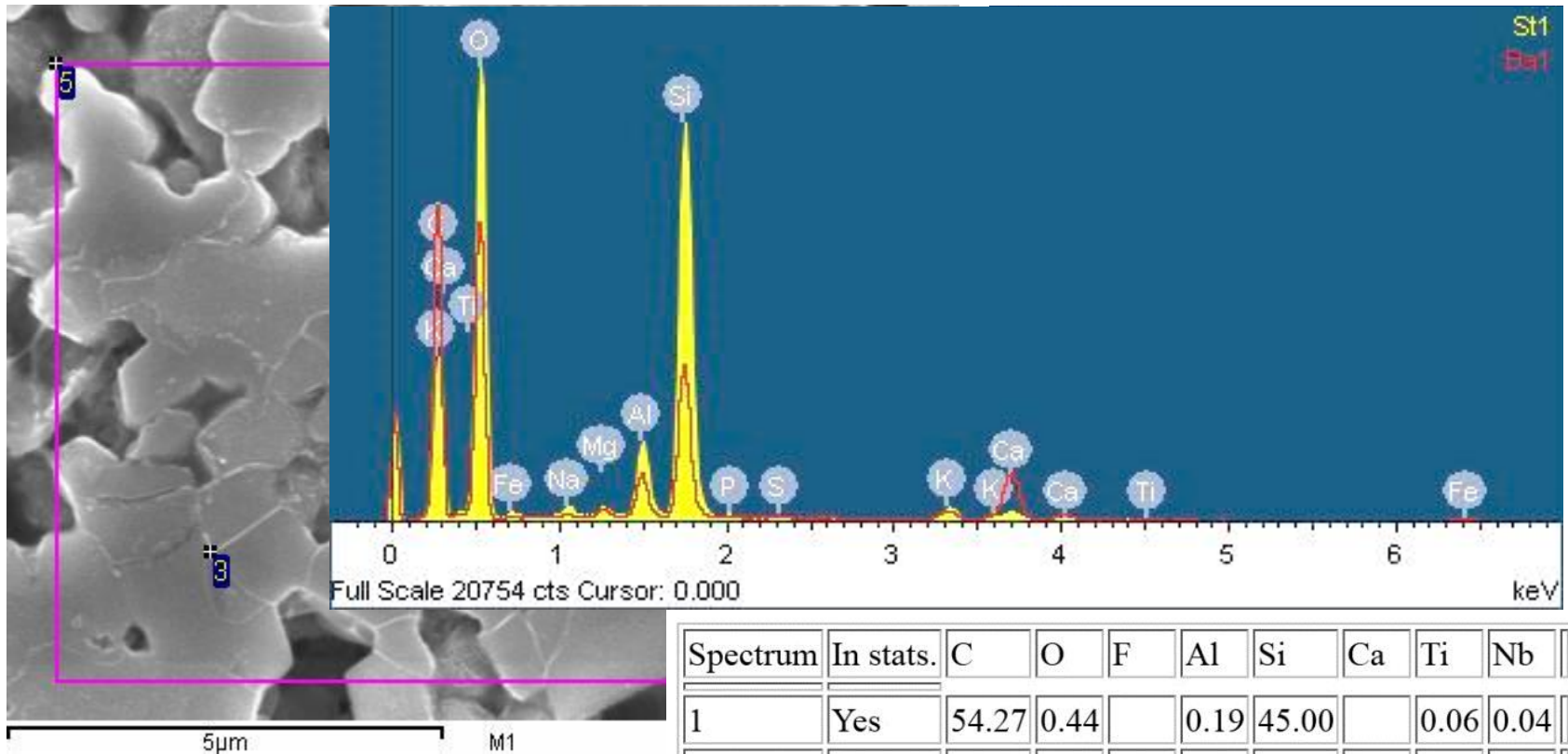
EPMA – electron probe microanalysis – special equipment with much higher electron beam intensity as in SEM – started about 70 years ago



- With new electron sources and X-ray detectors – EDS (from 1968) and lately WDS in SEM
- In present time – EPMA is a specialized SEM for precise and rapid WDS with several WDS systems

ARL EMX-SM equipment for EPMA of the mid -1960s. [R. Rinaldi and X.Llovet, Microsc. Microanal. 21 (2015) 1053]

# EDS – EDX - EDAX - As you know it....

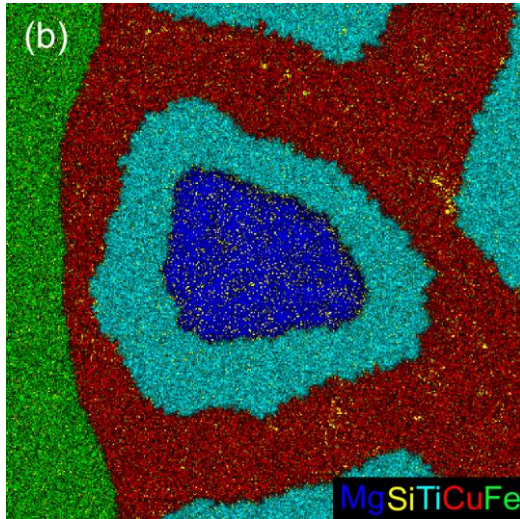


- qualitative elemental analysis
- quantitative elemental analysis

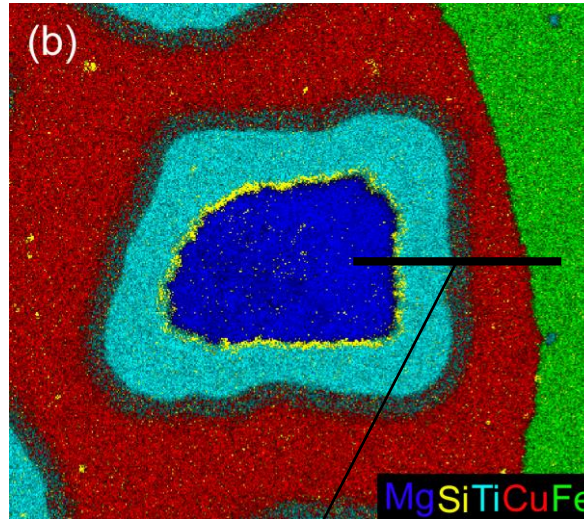
Spectrum	In stats.	C	O	F	Al	Si	Ca	Ti	Nb
1	Yes	54.27	0.44		0.19	45.00		0.06	0.04
2	Yes	53.90	0.78	0.43	0.30	44.50		0.03	0.07
3	Yes	54.10	1.34	0.54	0.52	43.02		0.27	0.21
4	Yes	58.54	1.46	1.71	0.26	37.68		0.19	0.16
5	Yes	53.40	1.53	1.90	0.28	42.24	0.16	0.25	0.25
Max.		58.54	1.53	1.90	0.52	45.00	0.16	0.27	0.25
Min.		53.40	0.44	0.43	0.19	37.68	0.16	0.03	0.04



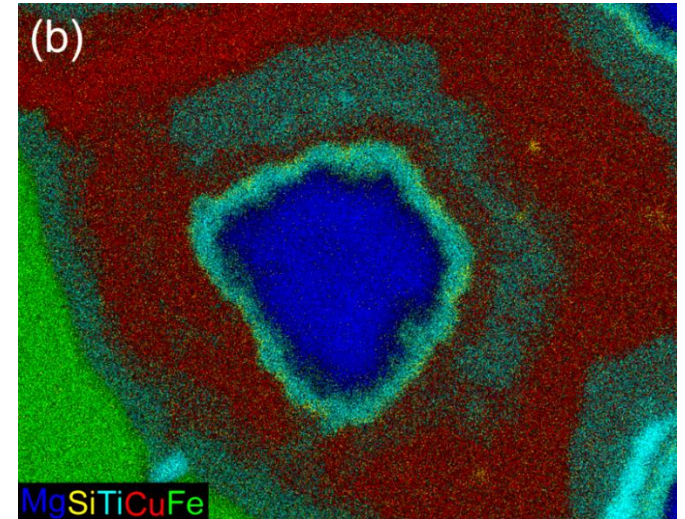
# X-ray elemental mapping



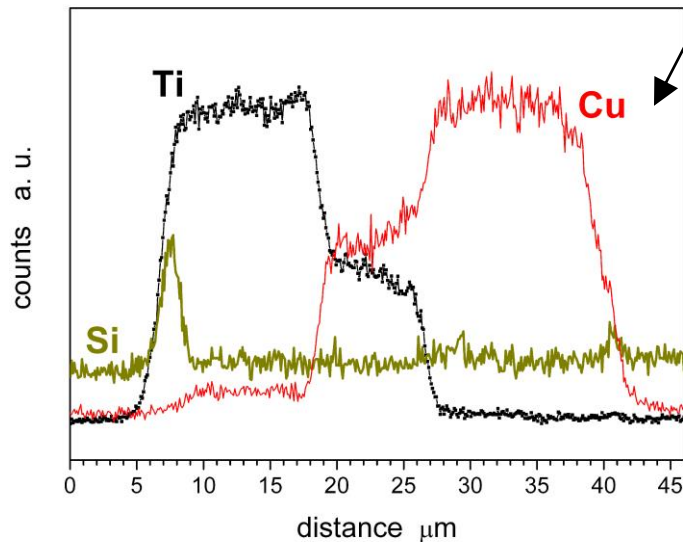
Before annealing



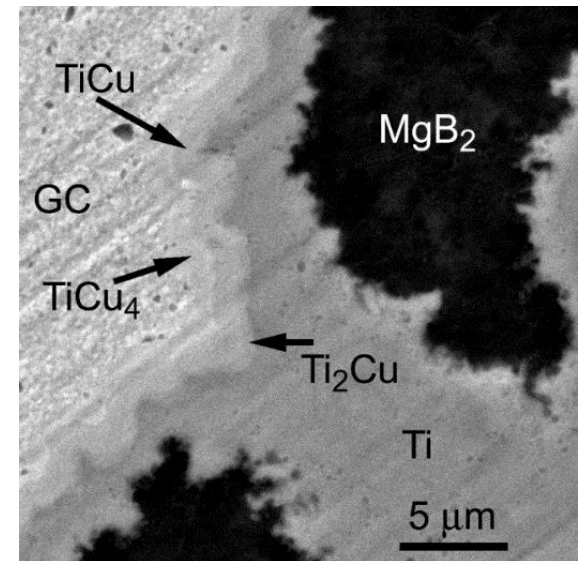
After optimal annealing



After excessive annealing



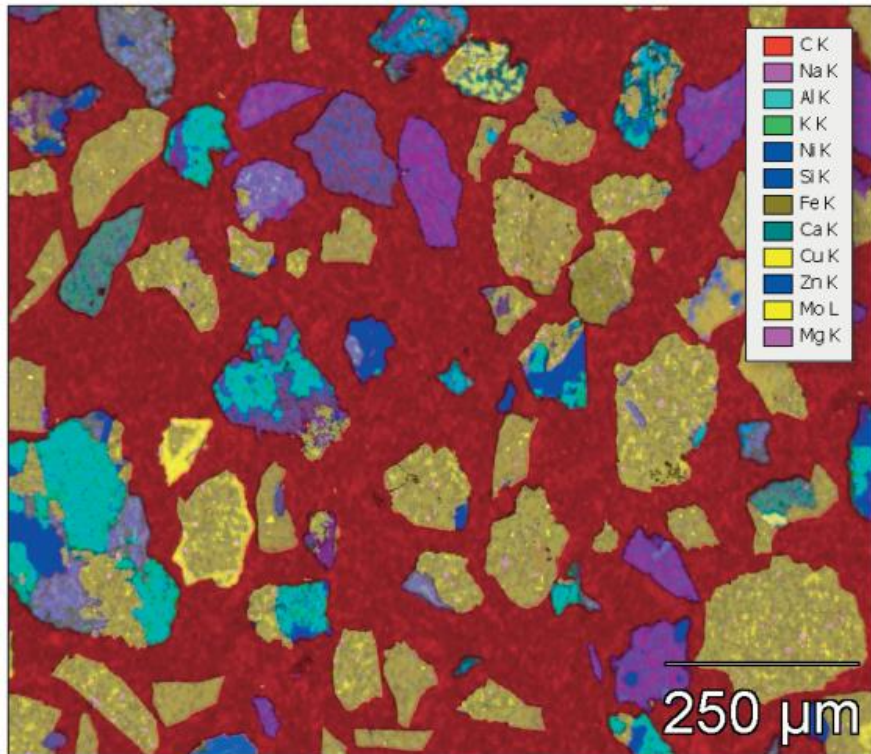
EDS line-scan



+ composition

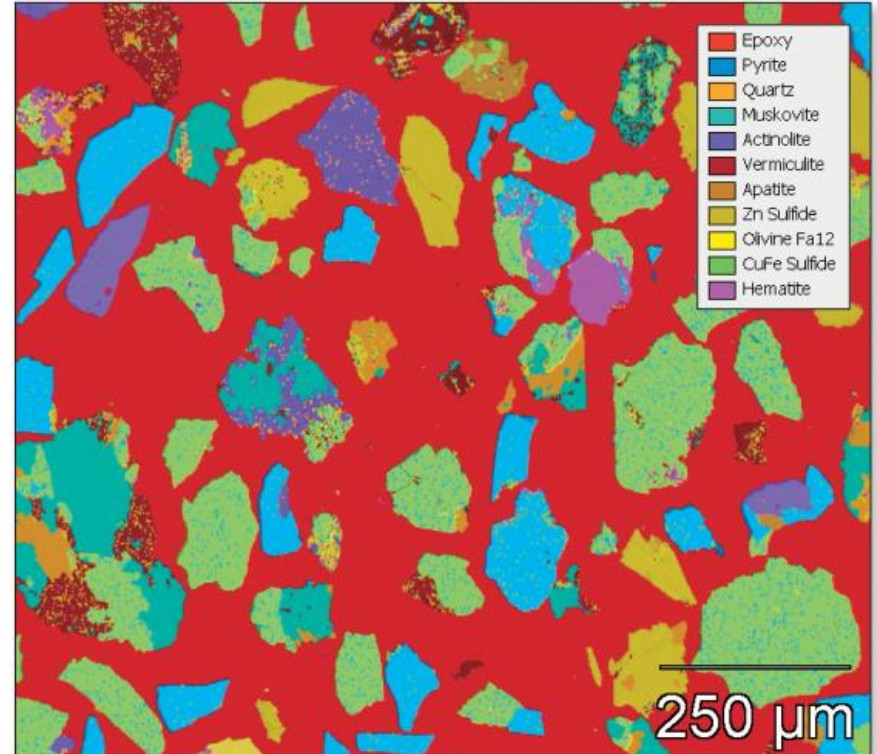


# Phase mapping



## Chemical element map

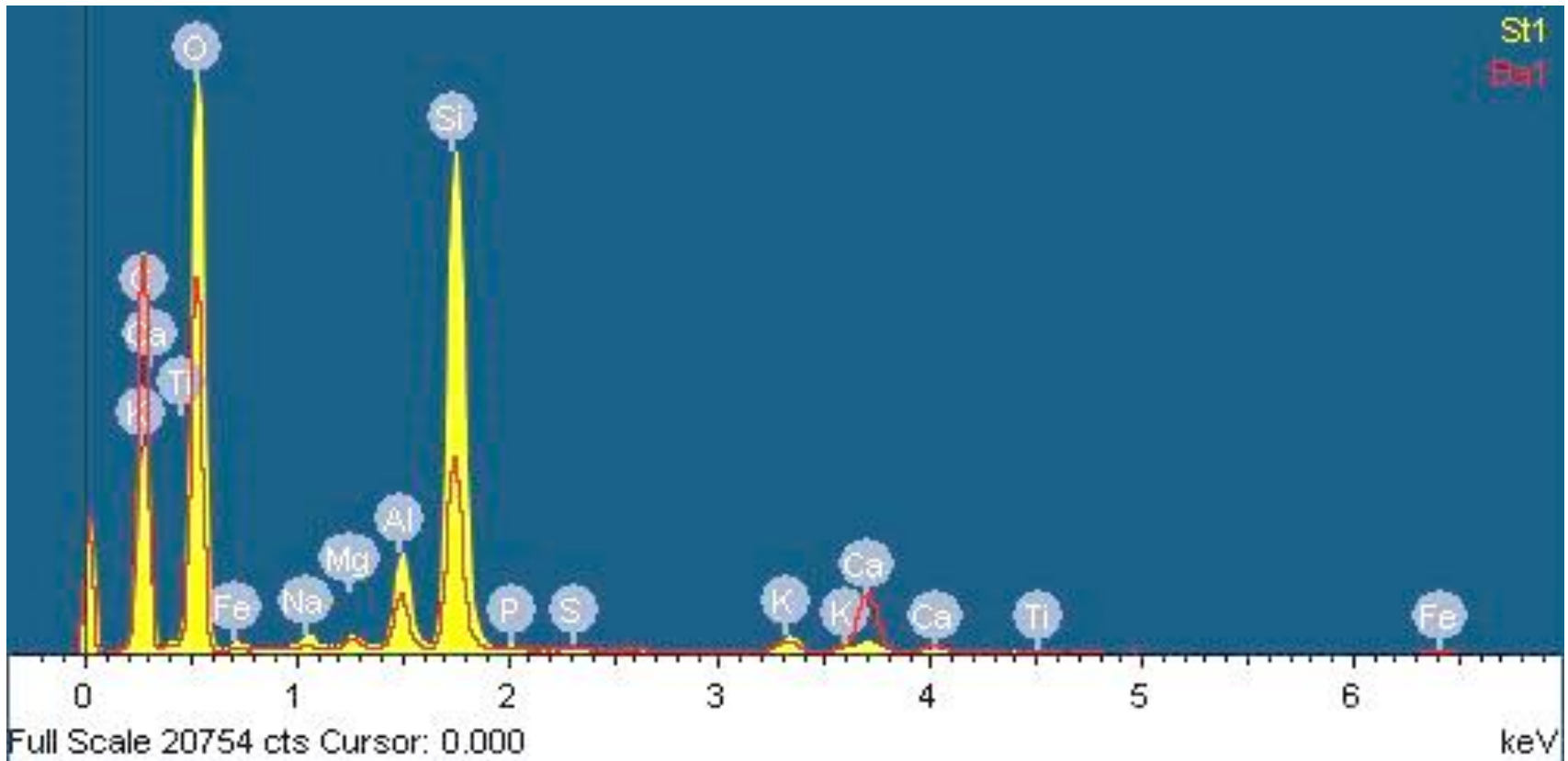
It shows the distribution of X-ray counts for all identified elements in the acquisition.



## Phase map

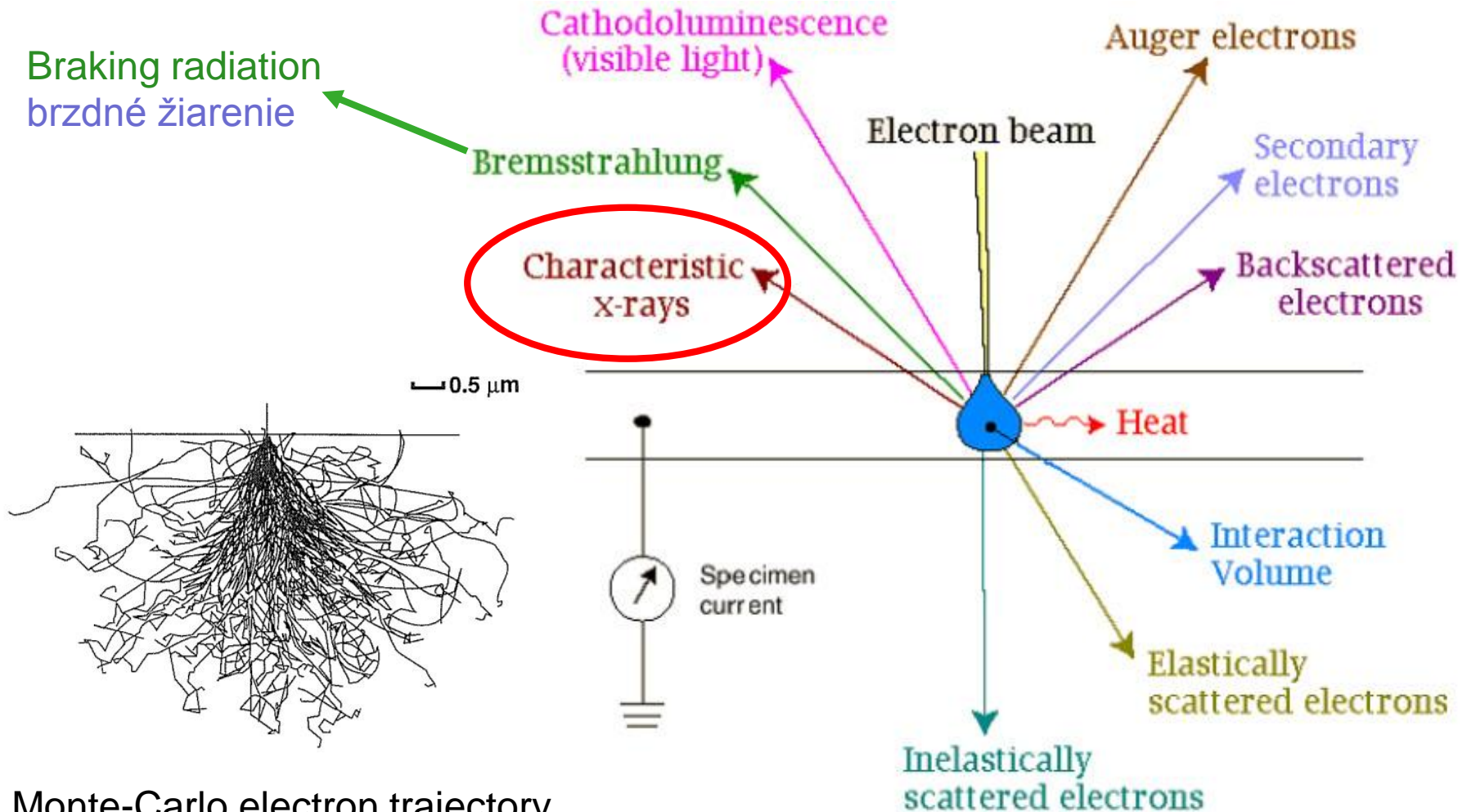
It groups together pixels with statistically similar X-ray spectra, performs a quantitative analysis of each phase, identifies the phases and compare them with a database to name them.

# The goal of this session



- To understand the origin and character of measured EDS spectra
- What information could be retrieved from
- What are the limits of spectra measurement and analysis
- How to optimize the measurements to obtain the optimal accuracy

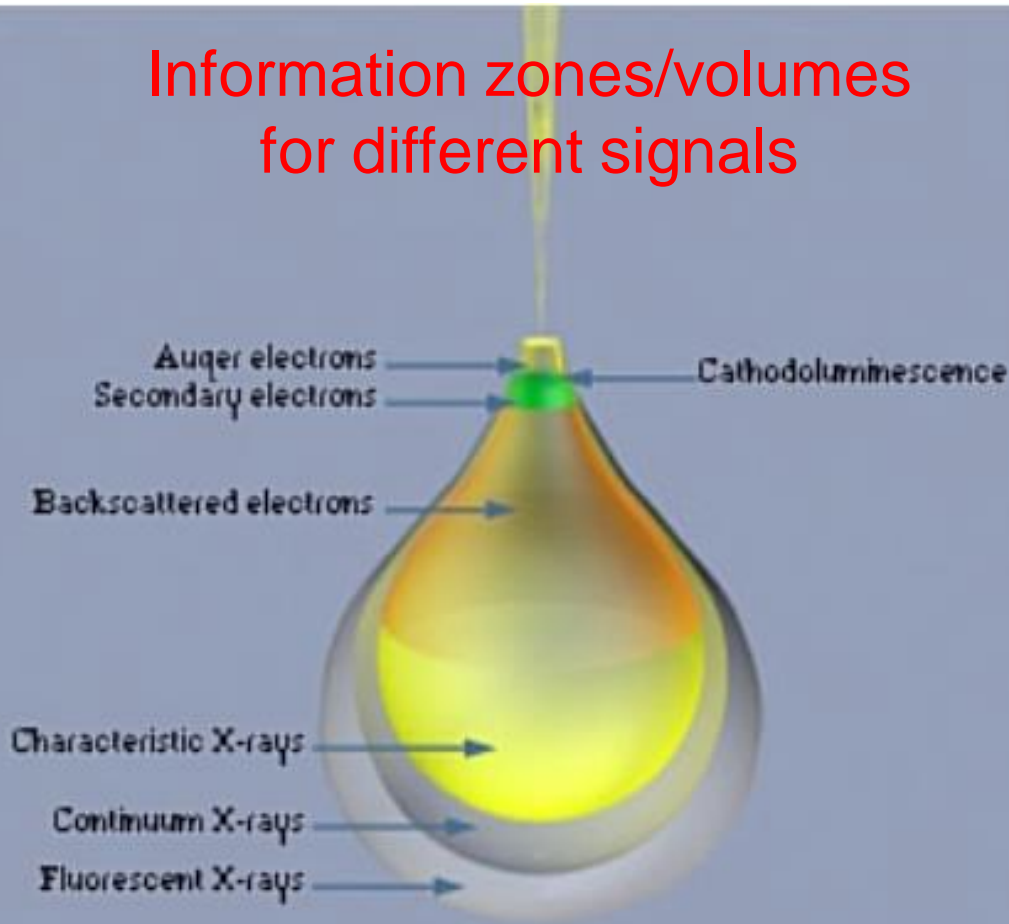
# SEM – electron beam interaction with a sample



Monte-Carlo electron trajectory simulations - **CASINO**

# Interaction versus information volume

## Information zones/volumes for different signals



[INCA Software Help document by Oxford Instruments]

## Interaction

### zone/volume -

zone/volume in which electron beam can excite atoms

### Information zone/ volume -

from which we measure relevant signal – for EDS it is different for every atom and every X-ray energy.

- necessary to know what processes are active in the zones



# Interaction volume – atom excitation

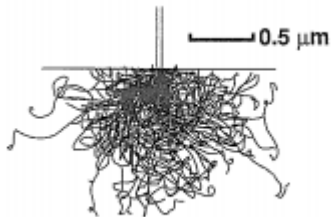
For atom excitation  $E_e > E_c$

Iron Fe

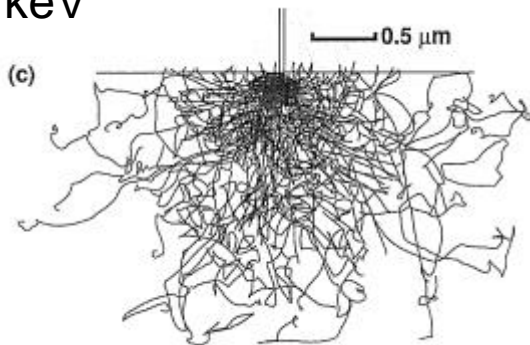
10 keV



20 keV



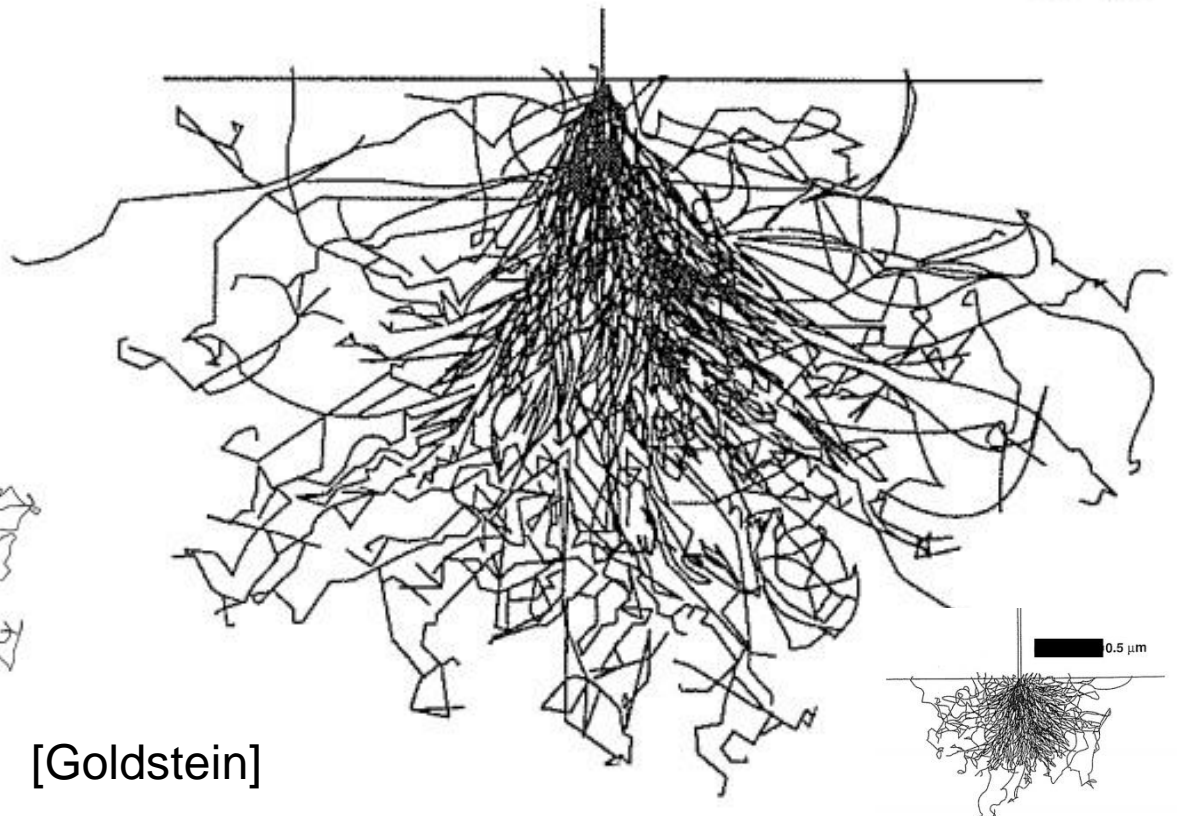
30 keV



[Goldstein]

Carbon C 20 keV

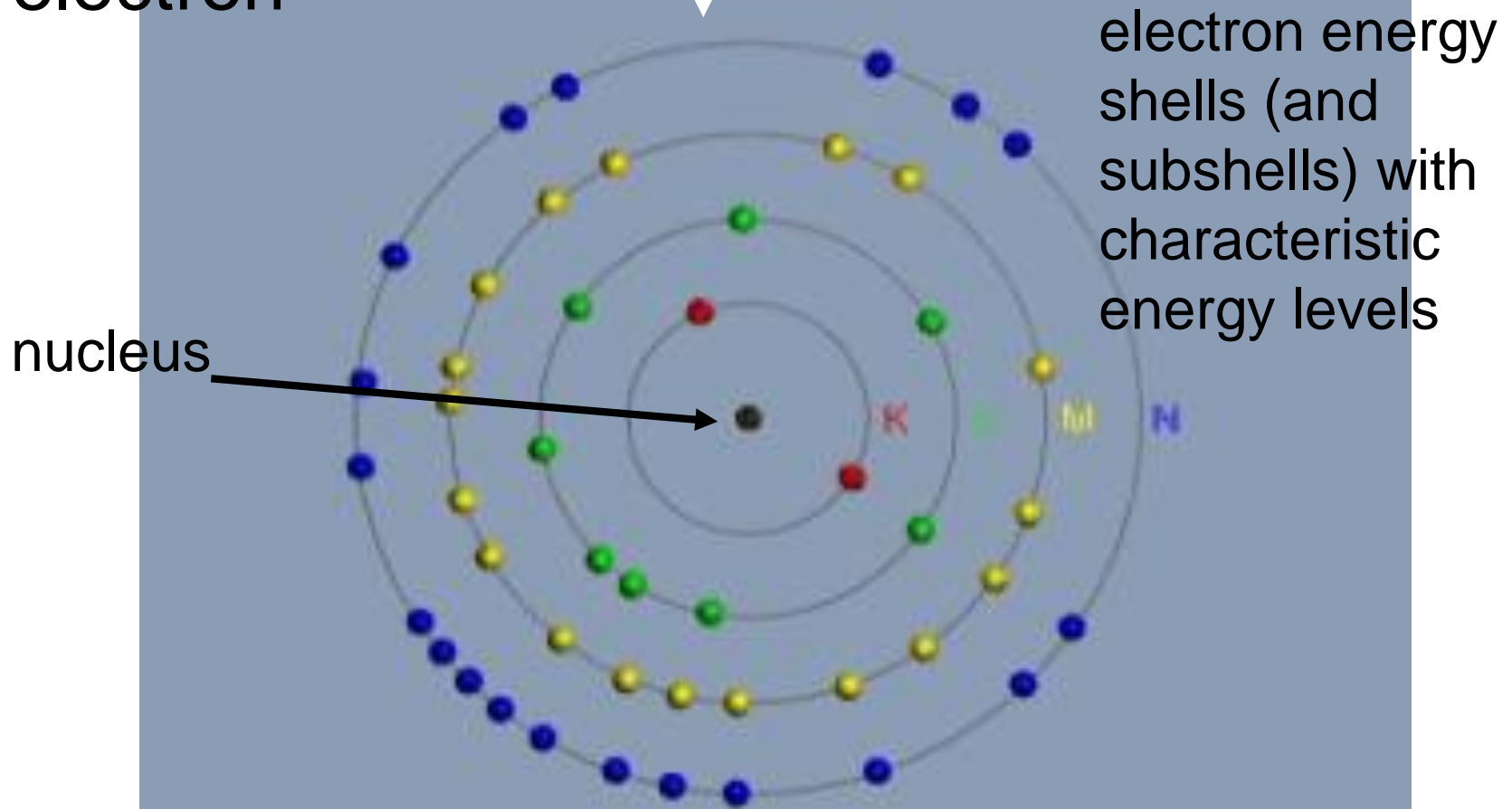
0.5 μm



Monte-Carlo electron trajectory simulations - CASINO

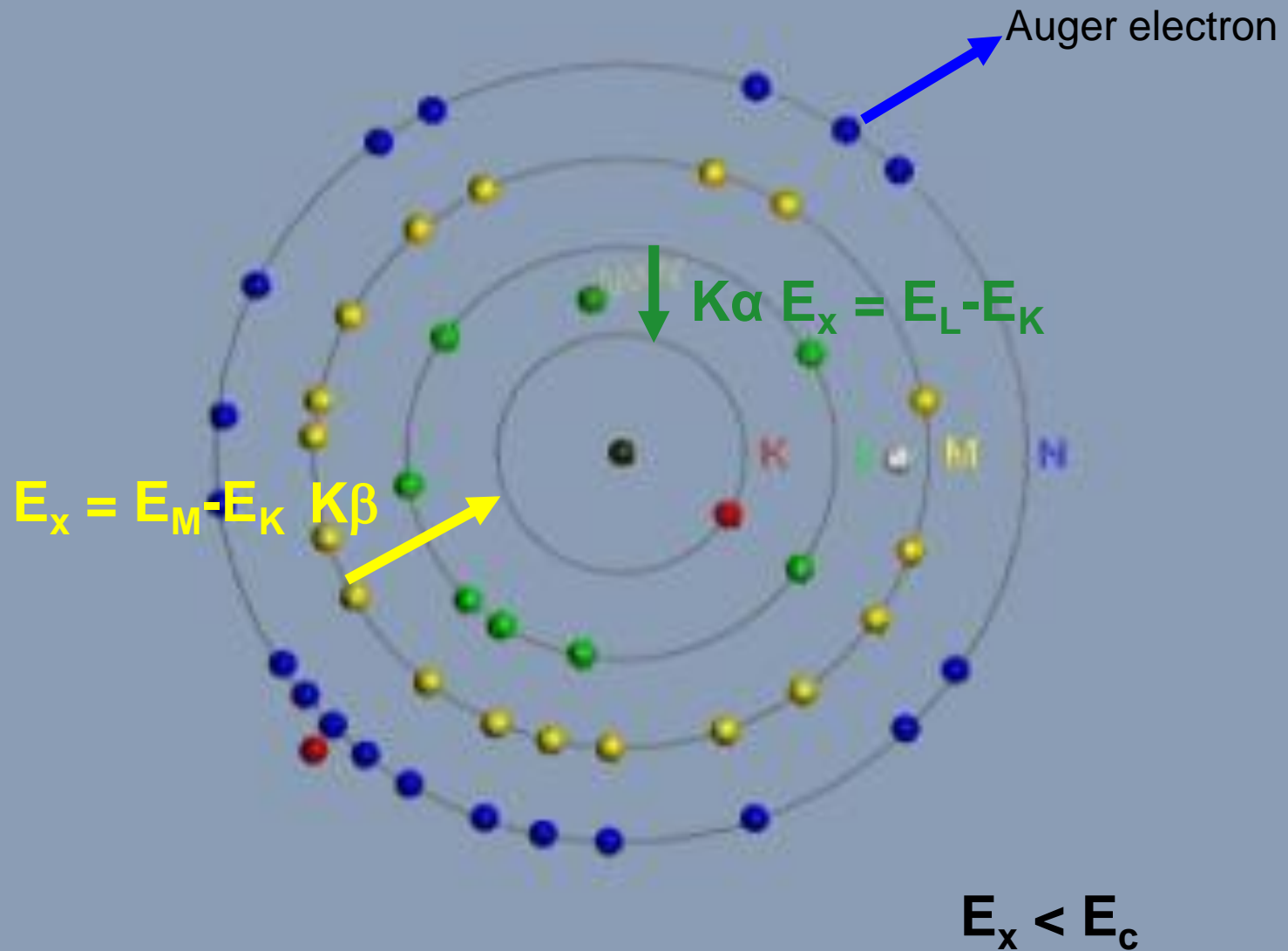
Silver Ag 20 keV

# Atom excitation by electron



Electron energy -  $E_e > E_c$  – critical ionization or excitation energy

# De-excitation

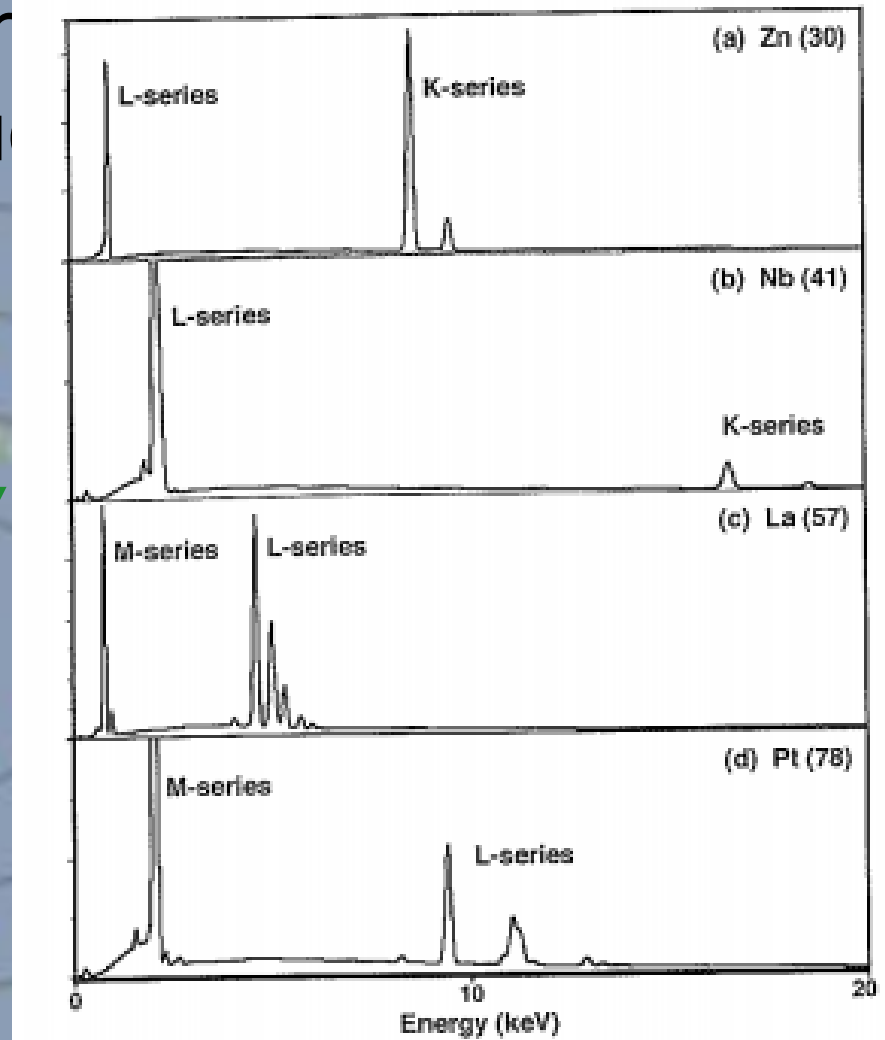






# De-excitation by characteristic X-ray production

$$E_x = E_M - E_K \quad K\beta$$



All vacancies should be filled to obtain equilibrium => all higher level transformations should run => the full family of characteristic lines should appear according to the number of electrons in the atom electron orbital

$$E_x < E_c$$

# Families of characteristic lines

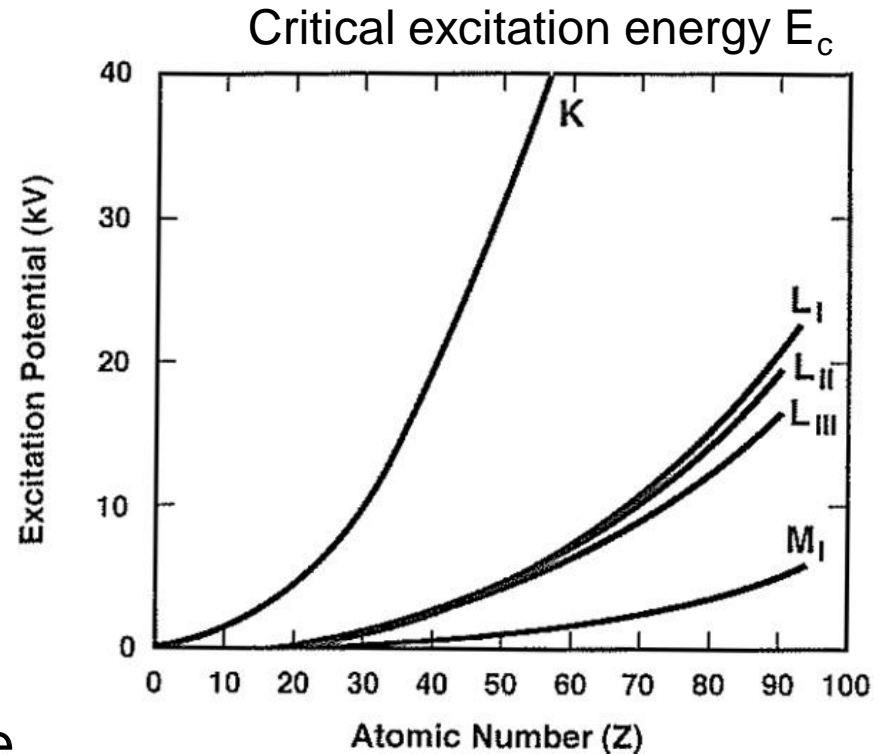
$$E_X < E_c$$

all  $E_X < E_c$  !!

$$E_{K\alpha} = E_K - E_L$$

$$E_{K\beta} = E_K - E_M \text{ (less probable)}$$

- The greater energy difference, the less probable and less intense X-ray line
- Table – **approximate** line weights for one element



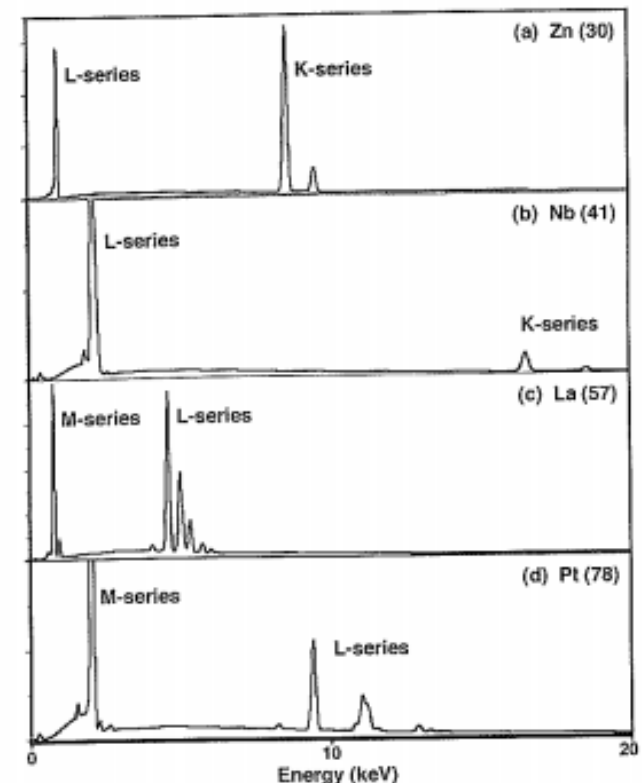


# Families of characteristic lines

**Table 6.3.** Weights of Lines

Family	Approximate line weights for <i>K</i> , <i>L</i> , or <i>M</i> shells
<i>K</i>	$K\alpha = 1, K\beta = 0.1$
<i>L</i>	$L\alpha = 1, L\beta_1 = 0.7, L\beta_2 = 0.2, L\gamma_1 = 0.08, L\gamma_3 = 0.03, L\delta = 0.04$
<i>M</i>	$M\alpha = 1, M\beta = 0.6, M\zeta = 0.06, M\gamma = 0.05, M\eta N_{IV} = 0.01$

- It is impossible to compare lines of different elements
- Useful guideline for qualitative and quantitative analysis – **all lines should be present** (they can overlap -> deconvolution)



[Goldstein]

# Cross section for inner shell ionization Q

$$Q = 6.51 \times 10^{-20} \frac{n_s b_s}{U E_c^2} \log_e(c_s U),$$

Účinný  
ionizačný  
prierez

Where  $n_s$  the number of electrons in shell or subshell,

$E_c$  is the critical ionization energy,

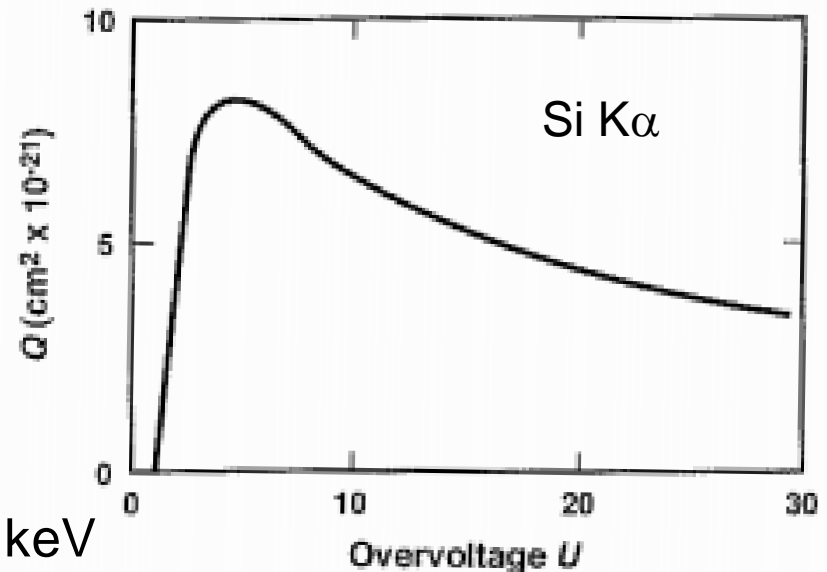
$b_s$  and  $c_s$  are constants for the particular shell,

$U$  is the overvoltage

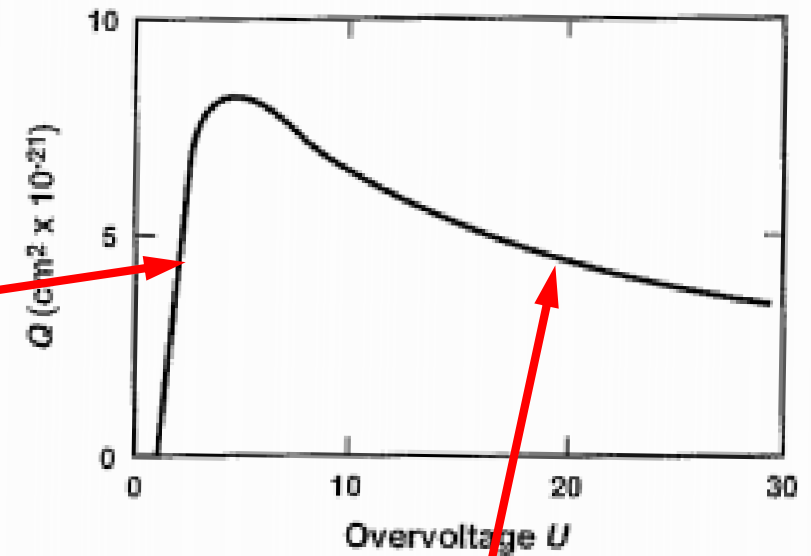
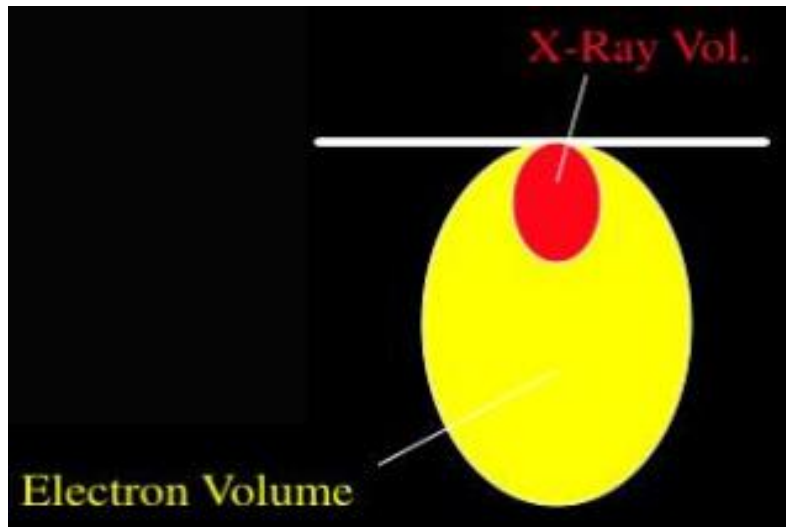
$$U = E/E_c \approx E/E_{x\max}$$

$E_{x\max}$  - the maximum energy of line which we want to analyze

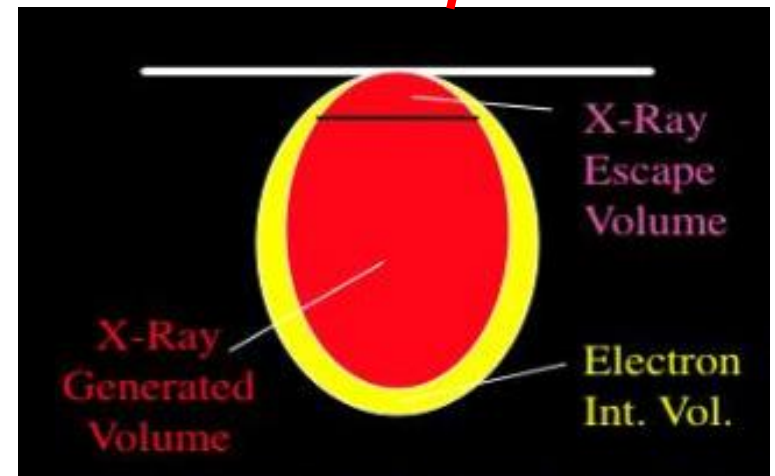
=> For Si K $\alpha$  (1.739 keV)  $E_{\text{opt}}$  is about 5 keV



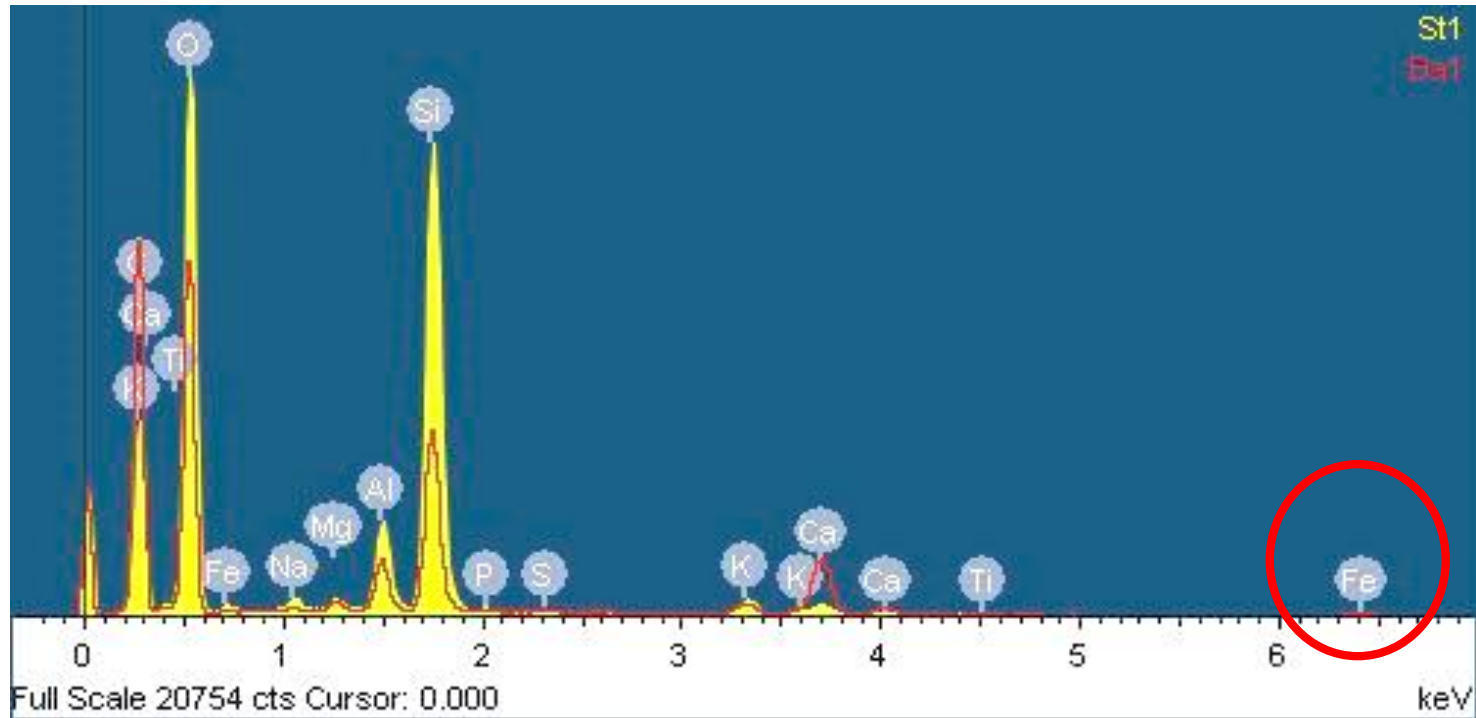
# Overvoltage



$U = 2 - 3$  is appropriate  
for the maximal ionization  
 $U \leq 10-20$  for the lowest peak  
of interest







For used acceleration voltage = 10 kV  $E = 10 \text{ keV}$ ,

Ideal overvoltage  $U = 3$ , obviously used  $\sim 2 - 2.5$

# Overvoltage

$E(\text{Mg K}\alpha) = 1.2536 \text{ keV}$

$E(\text{B K}\alpha) = 0.1833 \text{ keV}$

$\text{MgB}_2 \quad E = 5 \text{ keV}$

$U(\text{Mg K}\alpha) \cong 4$

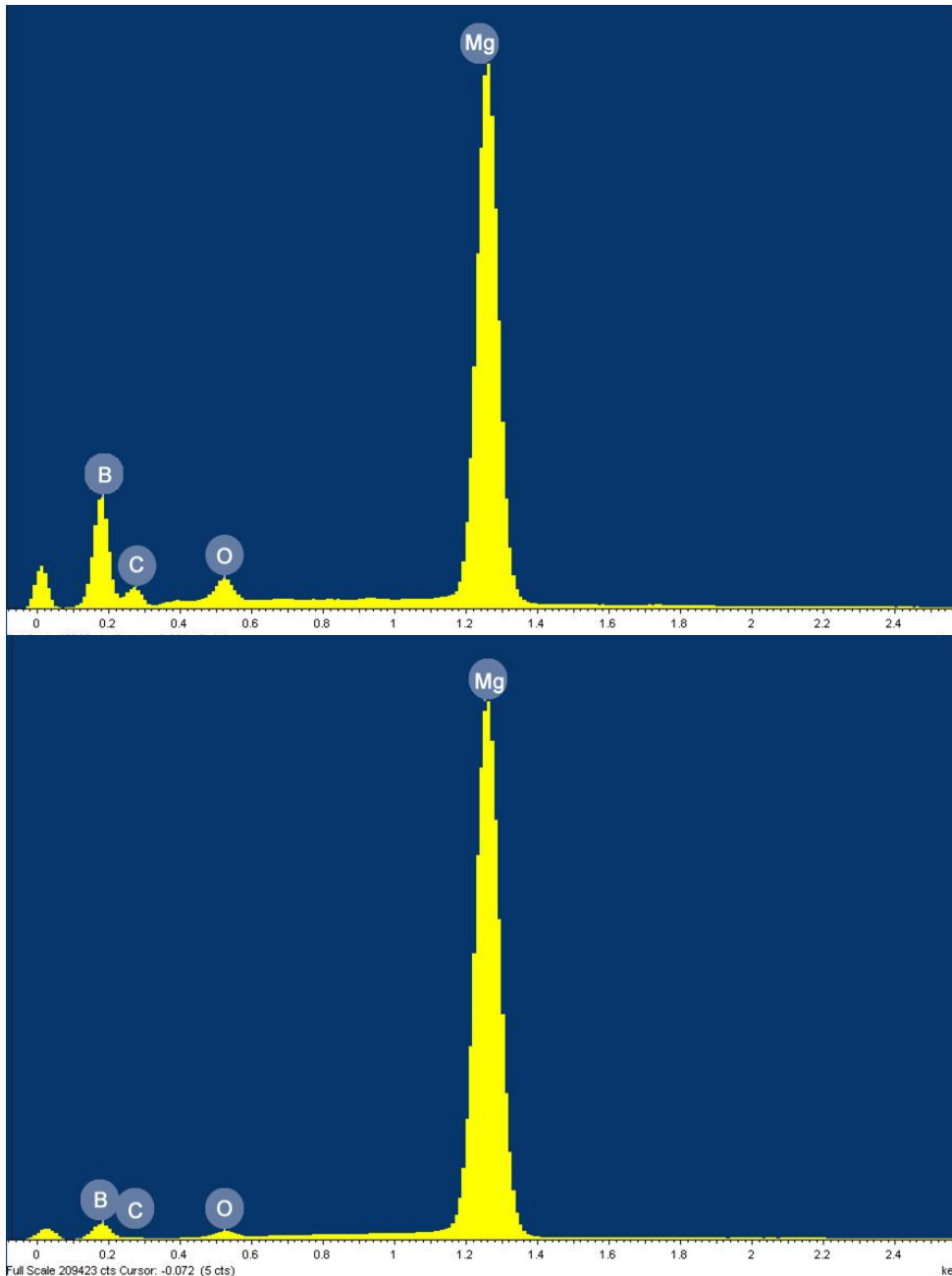
$U(\text{B K}\alpha) \cong 27$

$\text{MgB}_2 \quad E = 10 \text{ keV}$

$U(\text{Mg K}\alpha) \cong 8$

$U(\text{B K}\alpha) \cong 55$

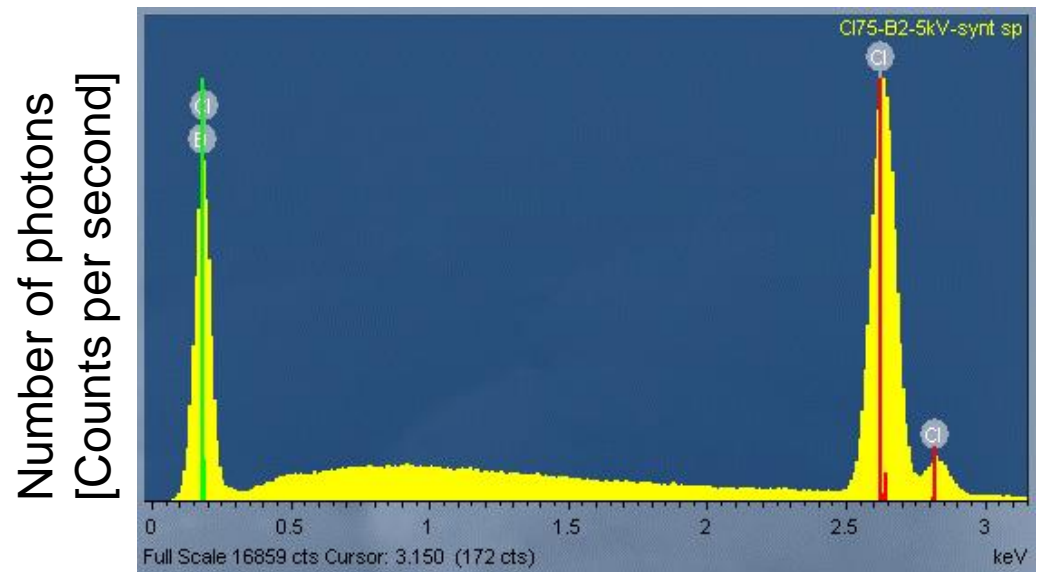
$\Rightarrow$  It decreases the accuracy of light element quantification



# X-ray generation

e-beam interaction with:

- electrons on inner energetic shells in atoms → X-ray photons with energies specific for emitting atoms  
→ **characteristic X-rays**
- Coulombic fields of the specimen atoms →  
**continuous spectrum background**

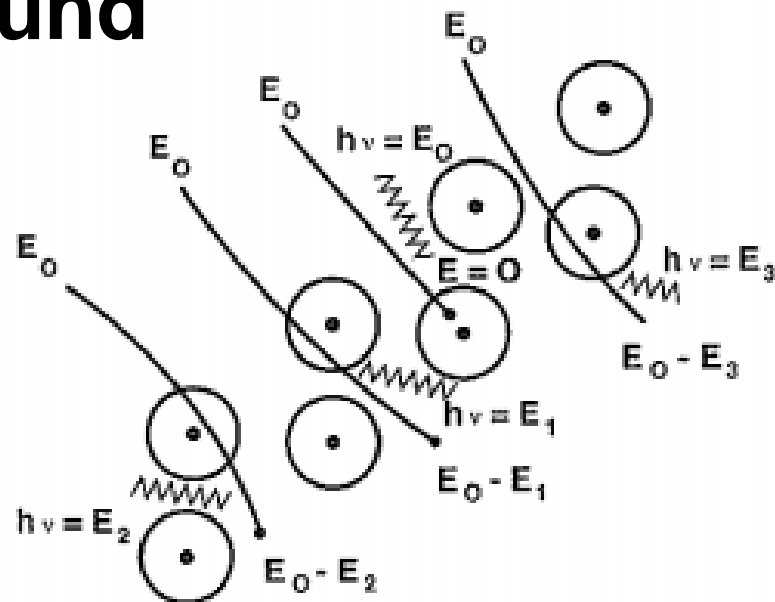


Energy of photons [keV]

# Spectrum background

- Bremsstrahlung = braking radiation = **brzdné žiarenie**
- Inelastic interaction – deceleration of  $e^-$  in the Coulombic field of atoms

$$\Delta E = E_p = h \nu \quad \lambda = h / E_p$$



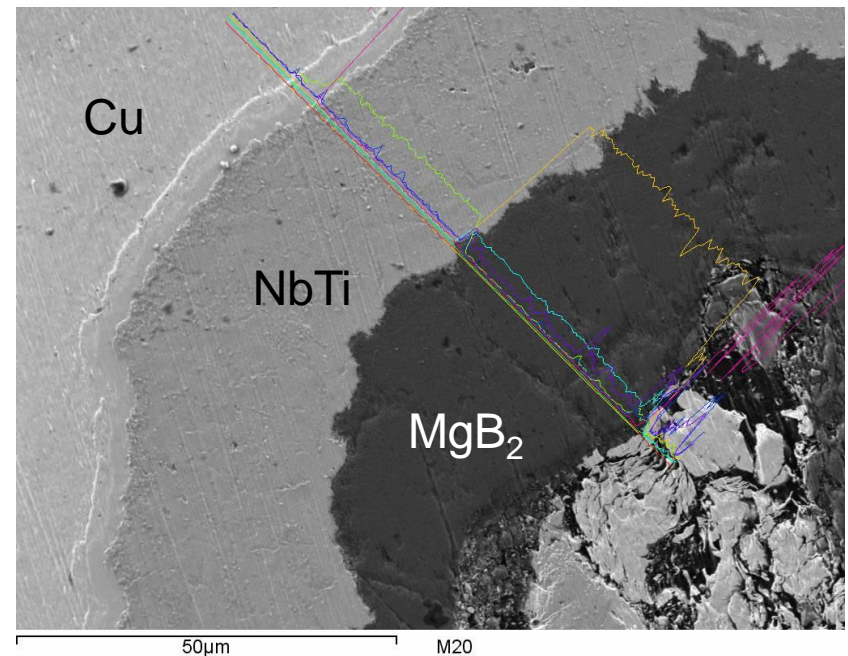
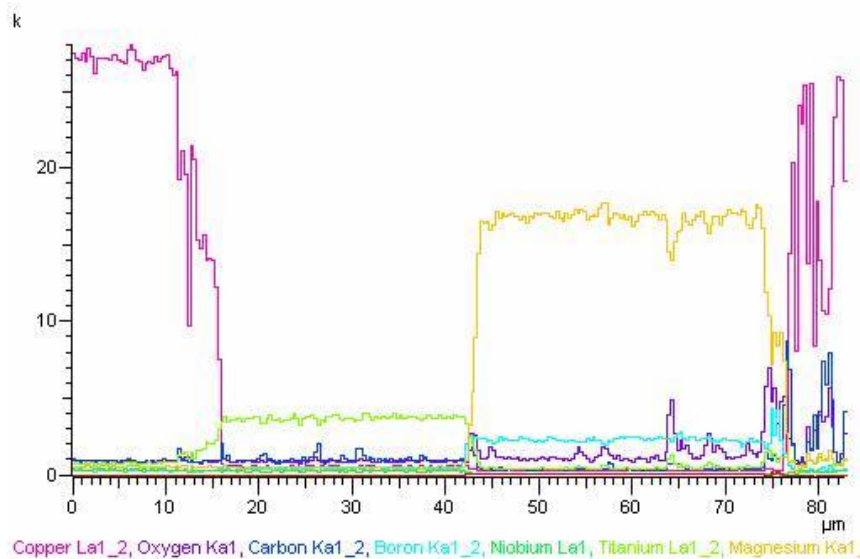
$$I_{cm} \approx i_p \bar{Z} \frac{E_0 - E_v}{E_v}$$

- Spectrum background – intensity  
( $i_p$  - current,  $\bar{Z}$  - mean atomic number,  
 $E_0$  - incident beam energy,  $E_v$  - continuum photon energy)

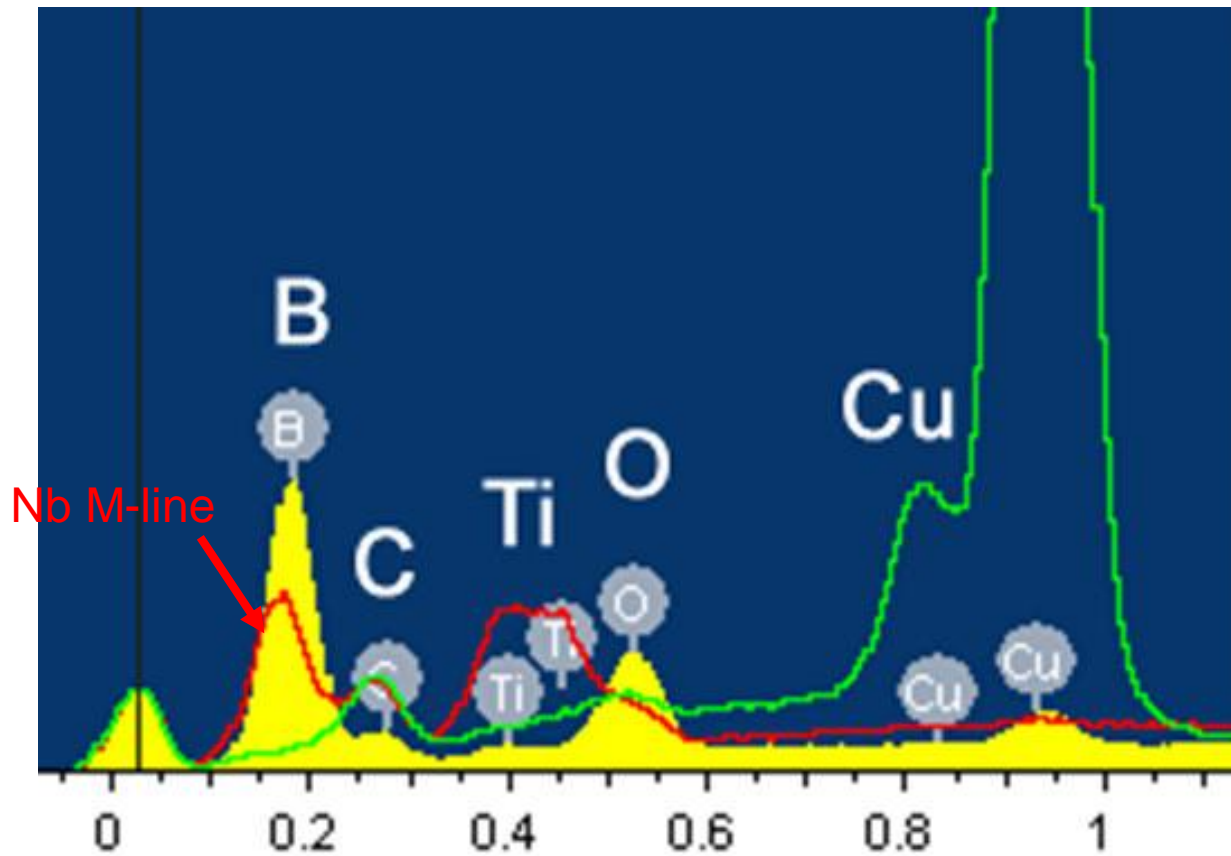
# Effect of spectrum background on line-scans

Line-scans of measured signals at corresponding photon energies

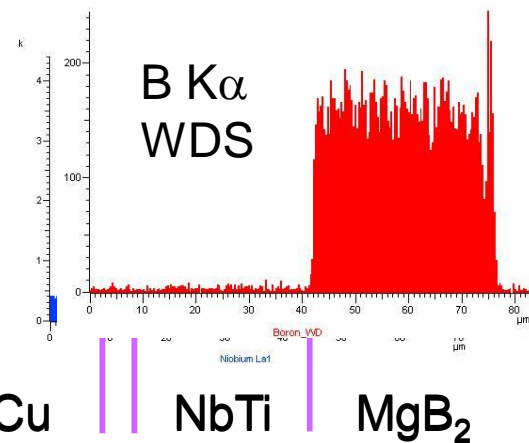
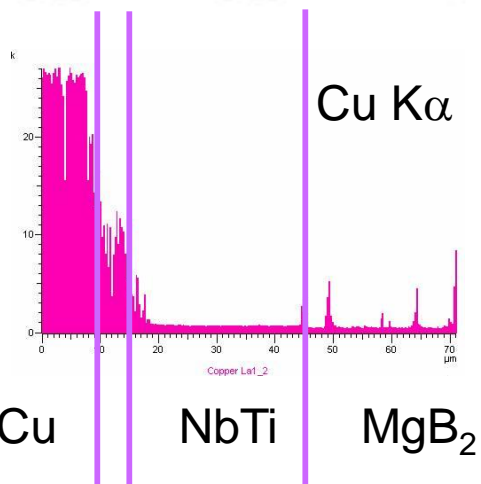
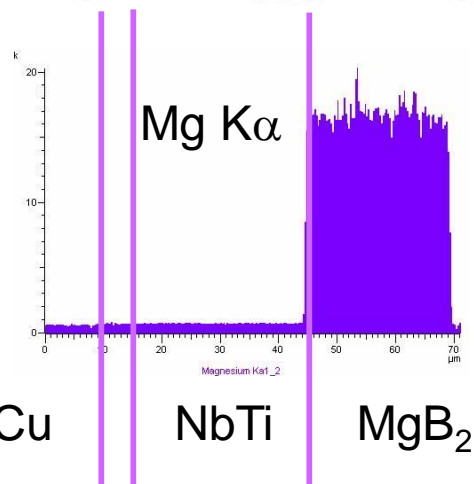
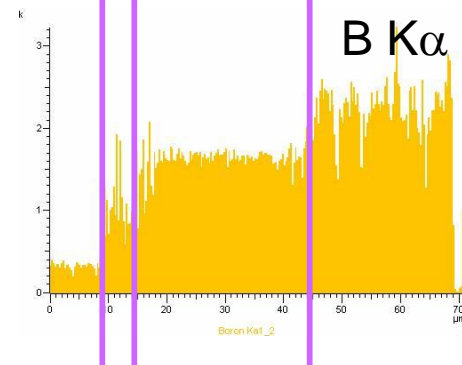
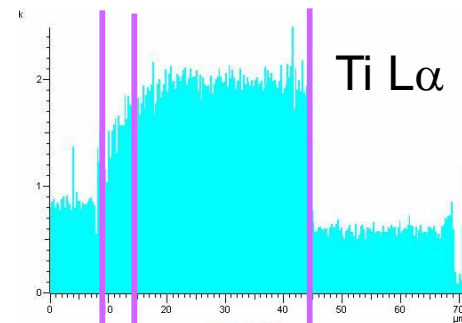
- no background or overlapping maxima correction !!!!
- no quantitative relation between scans of different atoms !!!!







# MgB<sub>2</sub>/NbTi/Cu



# X-ray absorption

Photons lose their energy on their path from the sample – by photoelectric absorption - transferring **the whole energy** to orbital electrons – the signal loses its intensity **but not its energy** - fortunately!!!

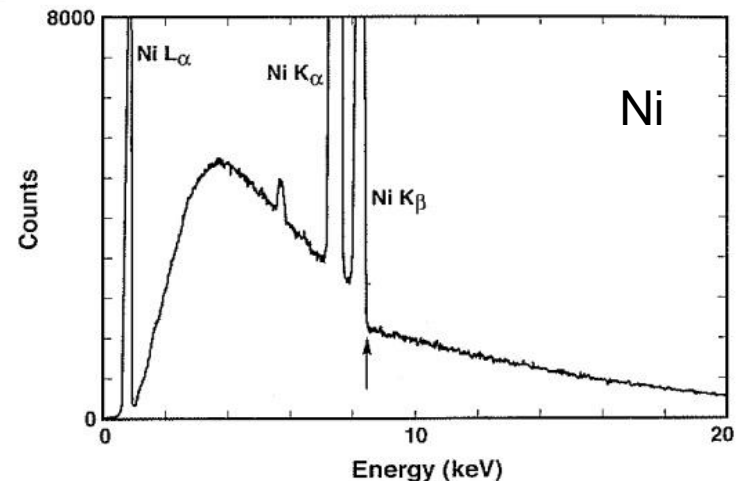
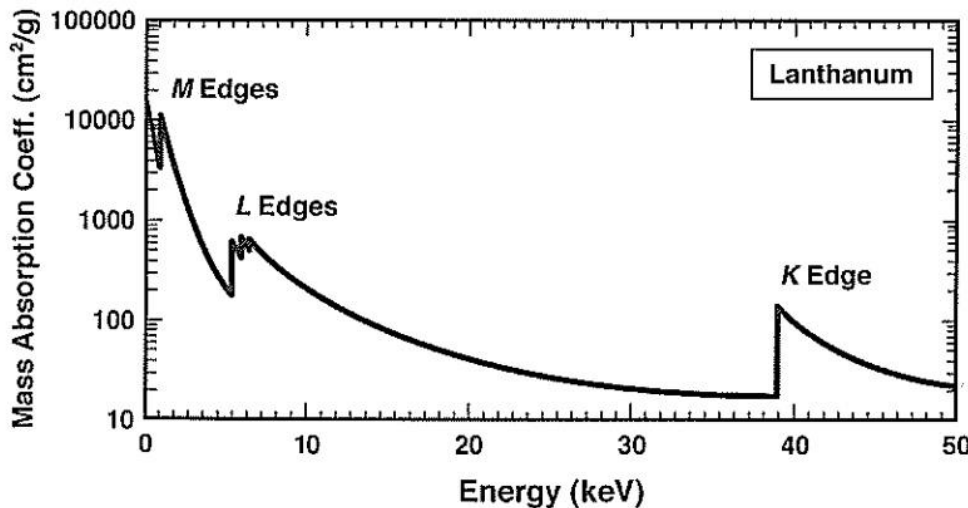
$$I = I_0 \exp \left[ - \left( \frac{\mu}{\rho} \right)_{\text{absorber}}^{\text{x-ray}} (\rho t) \right]$$

density

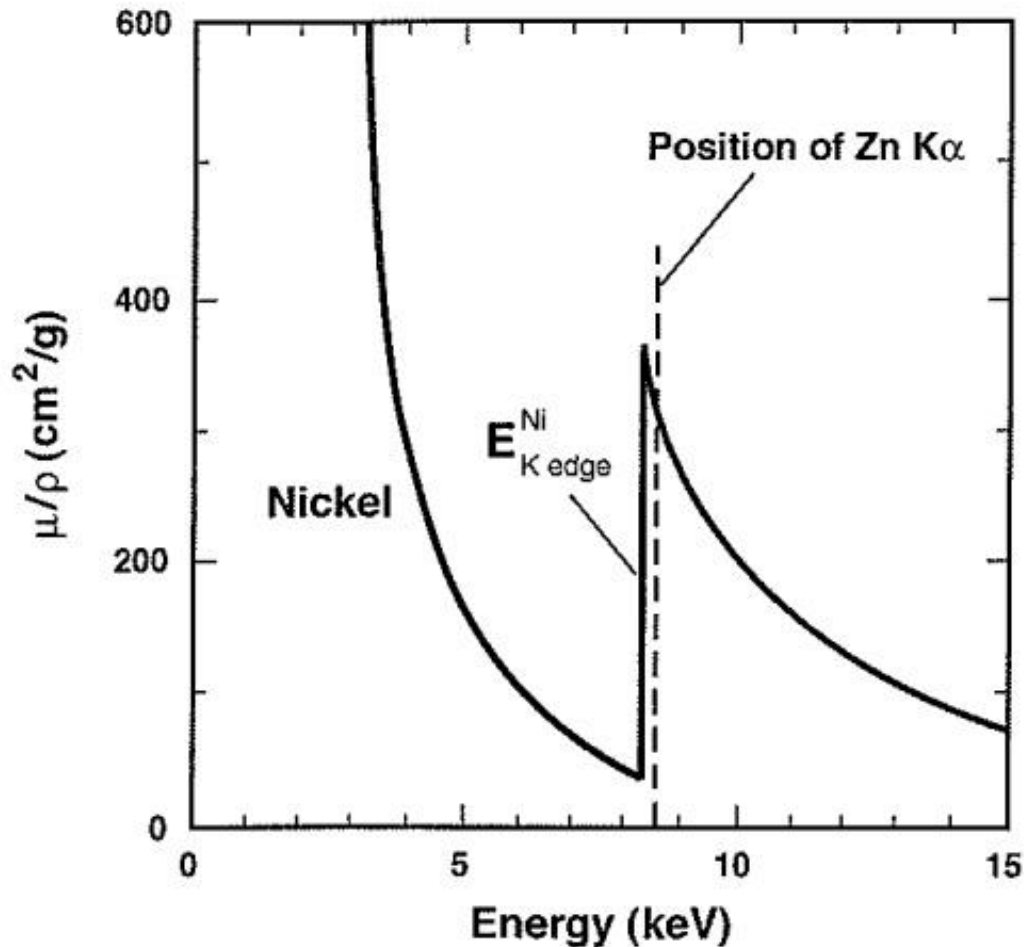
thickness

$$\left( \frac{\mu}{\rho} \right) = K Z^4 \left( \frac{1}{E} \right)^3$$

but with sharp jumps for energy just above  $E_c$  of absorber shells



# X-ray absorption



For Zn in Ni –  
as Zn K $\alpha$  has energy  
a bit higher as Ni K  
absorption edge -  
thus it can eject  
electrons from K Ni  
shell (fluorescence)  
and it is strongly  
absorbed.

# **X-ray fluorescence**

= X-ray induced emission of X-rays

- Consequence of X-ray absorption
- Photons with energy higher than  $E_c$  for a x-line can ionize atom and as a result a new photon can be emitted with  $E_x$
- If primary photon is a part of characteristic X-ray radiation -> characteristic fluorescence – it is significant only if the primary photon energy is up to 3 keV higher
- If primary photon is a part of braking radiation -> continuum fluorescence – the extra intensity range is about several %

# What does the “apparatus” really do?

- A. An e-beam of chosen energy scans a selected zone and the detector collects the emitted photons, analyzes their energy and creates a spectrum
- B. software analyze the peak positions and proposes possible element lines – the operator verifies them and verifies possible artifacts of measurement

*A+B – qualitative analysis*

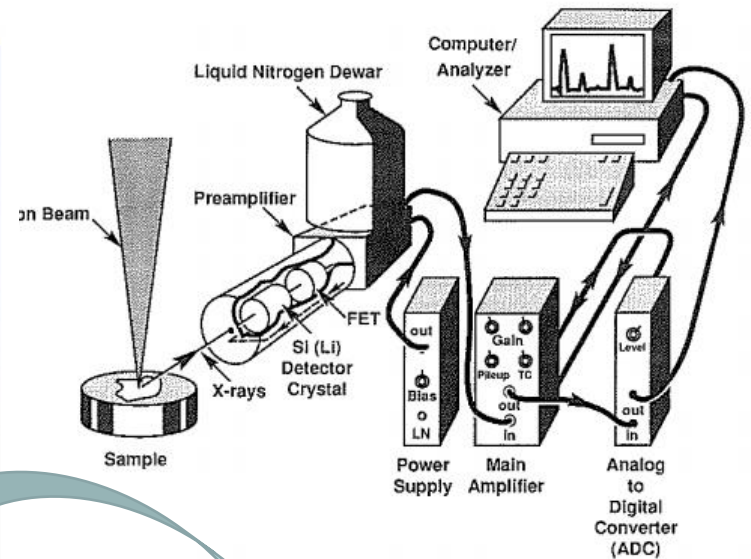
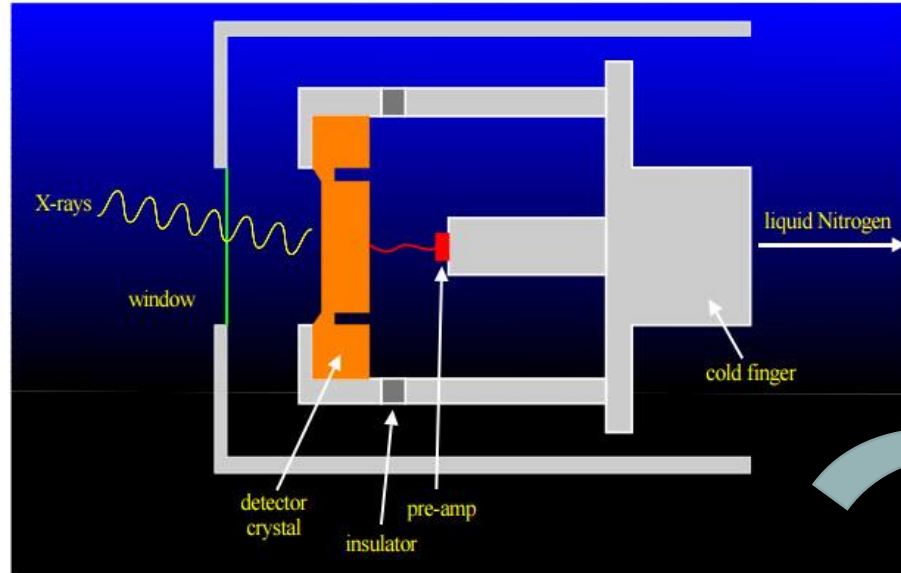
- C. software subtracts the spectrum background and calculate peak areas -  $I_i$  - very often automatically, but we can control it
- D. It calculates k-factor  $k = I_i / I_{(i)}$  for each found element
- E. By iterative process it re-calculates composition considering different physically based corrections and normalizes the composition to 100%

*C - E – quantitative analysis*

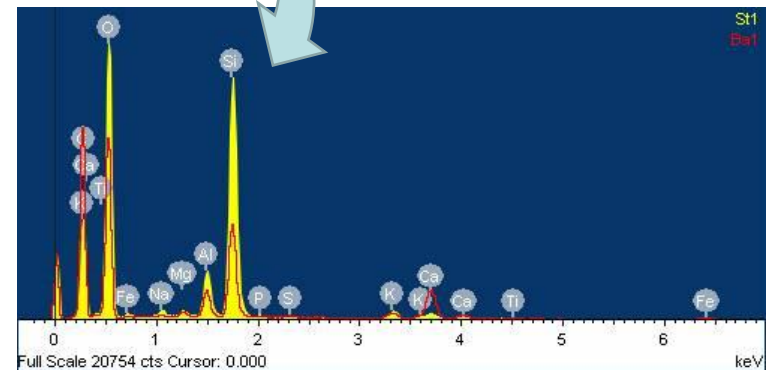


# A. Spectrum acquirement

## Si drift detector



X-ray photon  $\rightarrow$  photoelectron  $\rightarrow$  voltage pulse proportional to the photon energy  $\rightarrow$  **histogram of intensity by voltage** in counter and computer = spectrum – intensity [Cps – counts per second] dependance on energy [keV]



# Spectral artifacts from detection process

- **Peak broadening** – natural width of x-ray peaks – FWHM 2-10 eV (dependant on energy) → modern detector resolution of about 120-130 eV for Mn  $K\alpha$  ( at 5.9 keV) – due to statistic character of detection
- **Peak distortion** – deviation from Gaussian shape and background increasing at energies below the peaks
- **“Sum” or “coincidence” or “pileup” peaks** with the sum energy ( e.g.  $2K\alpha$ ) + background deformation ⇒  
(decrease of X-ray signal by decreasing of e. beam current or increasing of detector distance or change of time constant)

$$\text{real time} = \text{dead time} + \text{live time}$$

Dead time – characterise the detection process – for quantification it is necessary to use similar conditions, thus the best value for any used equipment is estimated (e.g. 30-33% UMMS)

## B. Qualitative analysis

- What do I want to analyze? Presence of major and minor elements
- Measuring conditions – voltage (appropriate overvoltage), current, process time, dead time
- Verifying of measured peaks (Presence of line families!!)
- Removing of spectra artifacts
- Only statistically significant peaks

$$P > 3 (N_B)^{1/2}$$

P – peak,  $N_B$  – background at peak energy

- Possible additive measurements if peak overlapping (change of voltage, process time, WDS, ...)

## C. Quantitative analysis

- What do I want to measure?
- First – accurate qualitative analysis !
- Peak overlapping - deconvolution
- Background subtraction (modeling, filtering, interpolation or extrapolation from background near the peak )

Only 1.68 wt% of Mn in a steel

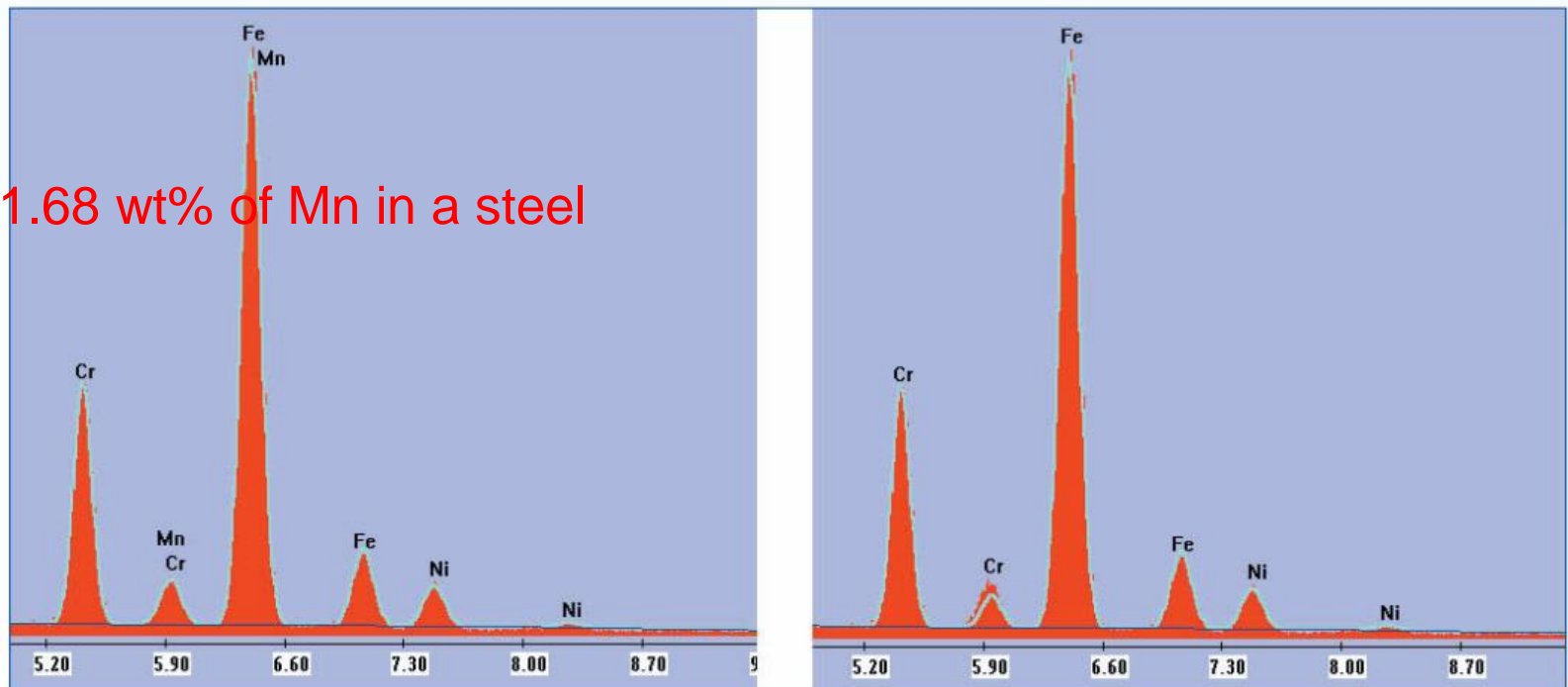


Figure 3 shows the correct and incorrect identification for the Cr and Mn overlap in stainless steel.

## D. Quantitative analysis

- k - factors  $k = I_i / I_{(i)} = C_i / C_{(i)}$  Castaing's first approximation to quantitative analysis

$I_i$  is measured "i" peak intensity without background

$I_{(i)}$  is standard "i" peak intensity without background

$C_i$  is weight fraction of i-th element in the sample

$C_{(i)}$  is weight fraction of i-th element in the standard



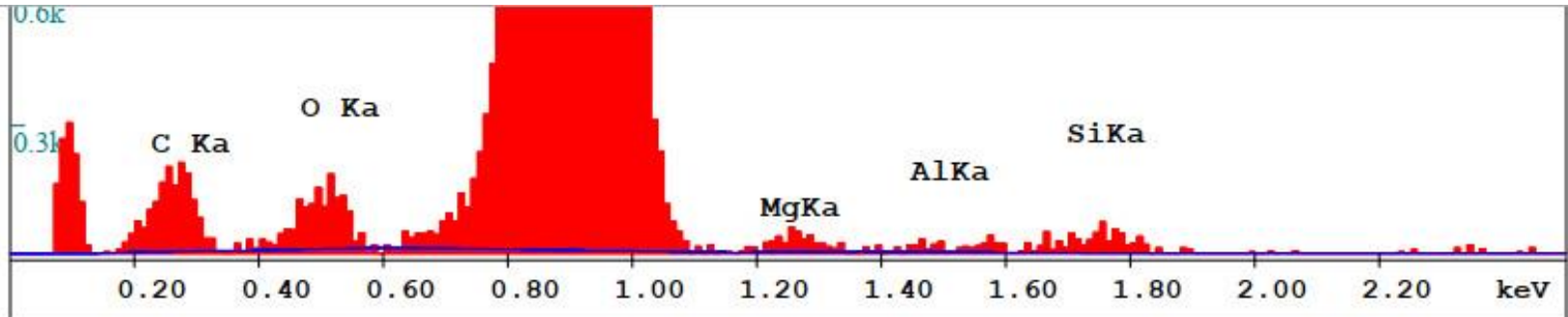
## E. Matrix effect correction

Matrix effect can be divided into 3 effects:

- atomic number  $Z_i$
- x-ray absorption  $A_i$
- x-ray fluorescence  $F_i$

$$C_i / C_{(i)} = [ZAF]_i \cdot I_i / I_{(i)} = [ZAF]_i \cdot k$$

# ZAF correction



EDAX ZAF Quantification (Standardless)  
Element Normalized  
SEC Table : Default

Element	Wt %	At %	K-Ratio	Z	A	F
C K	1.64	7.91	0.0110	1.3756	0.4867	1.0001
O K	0.60	2.17	0.0065	1.3494	0.8084	1.0016
CuL	97.40	89.04	0.9619	0.9891	0.9985	1.0000
MgK	0.37	0.88	0.0035	1.2489	0.7526	1.0000
Total	100.00	100.00				

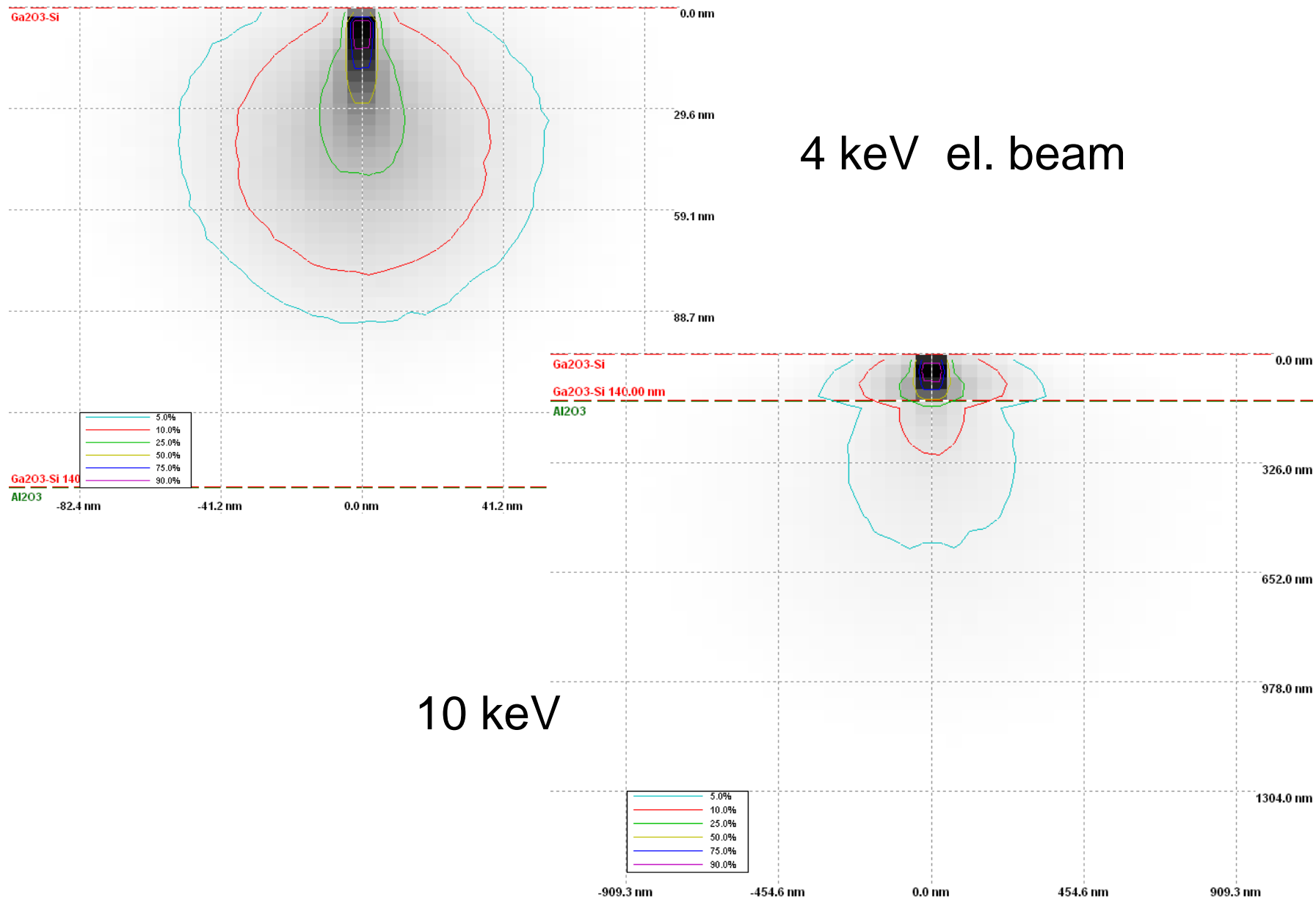
Element	Net Inte.	Bkgd Inte.	Inte. Error	P/B
C K	2.78	0.09	2.93	32.63
O K	1.98	0.20	3.68	10.07
CuL	163.02	0.15	0.37	1120.45
MgK	0.70	0.06	6.18	10.72

## C-D-E. Quantitative analysis

- Remember that the quantification routine is designed based on the three assumptions of microanalysis:

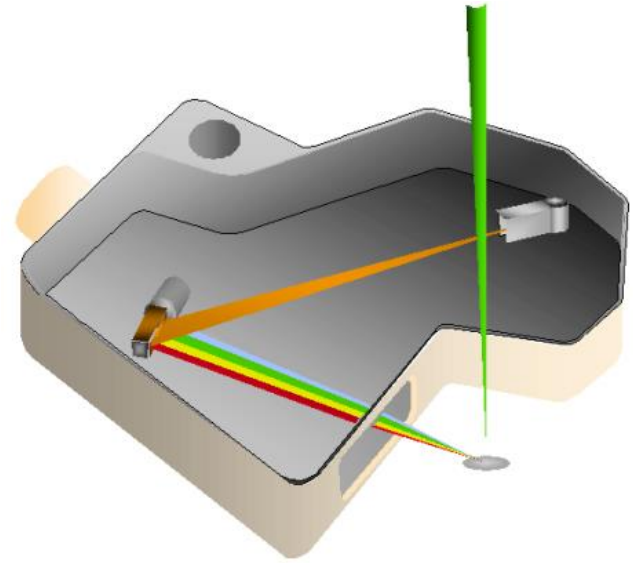
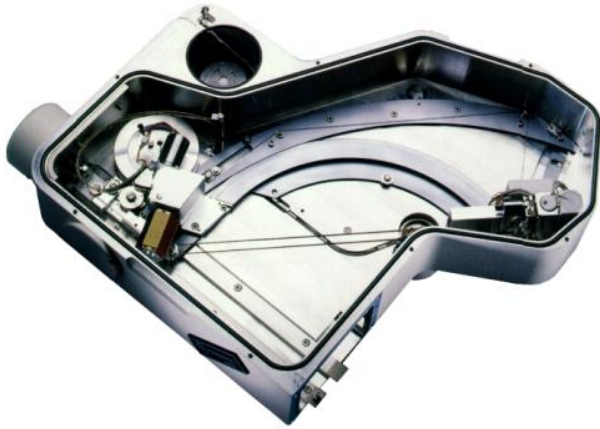
1. The sample is smooth and polished.
2. The sample is homogeneous (minimally in the actual information volume).
3. The sample is infinitely thick to the electron beam.

=> “Bulk method”



$\text{Ga}_2\text{O}_3(140 \text{ nm})$  on  $\text{Al}_2\text{O}_3$  substrate

# WDS



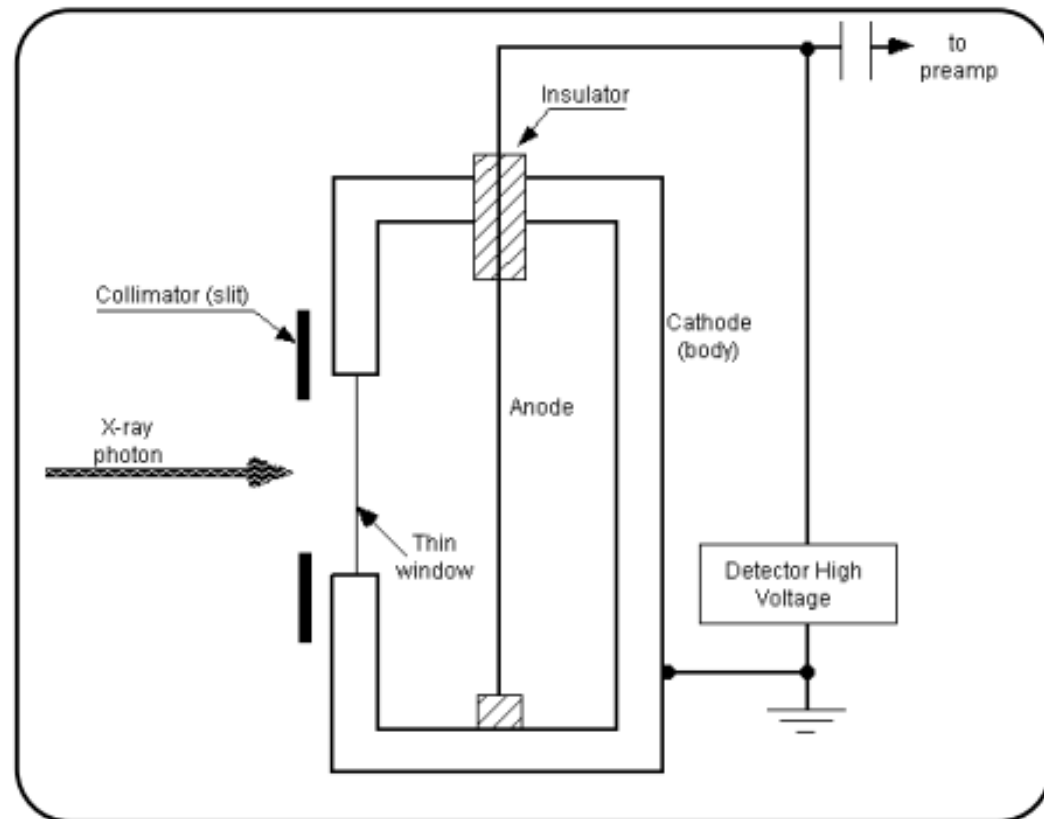
- The same physical concept based on characteristic X-ray detection
- the measured X-rays are selected by diffraction on built-in crystals to measure signal intensity with high energy resolution of 2 – 40 eV (120-130 eV for EDS)
- Gas proportional counter is used as detector of X-rays without artifacts present in semiconducting EDS detectors.



# WDS – X-ray signal detection

gas proportional counter

- Excellent dynamic range  
0 – 50000 cps or more
- Wide range of energies
- High collection efficiency



# Diffraction on crystals

Bragg condition

$$n\lambda = 2d \sin \theta$$

$d$  – the interplanar distance

$$E = hF = \frac{hc}{\lambda}$$

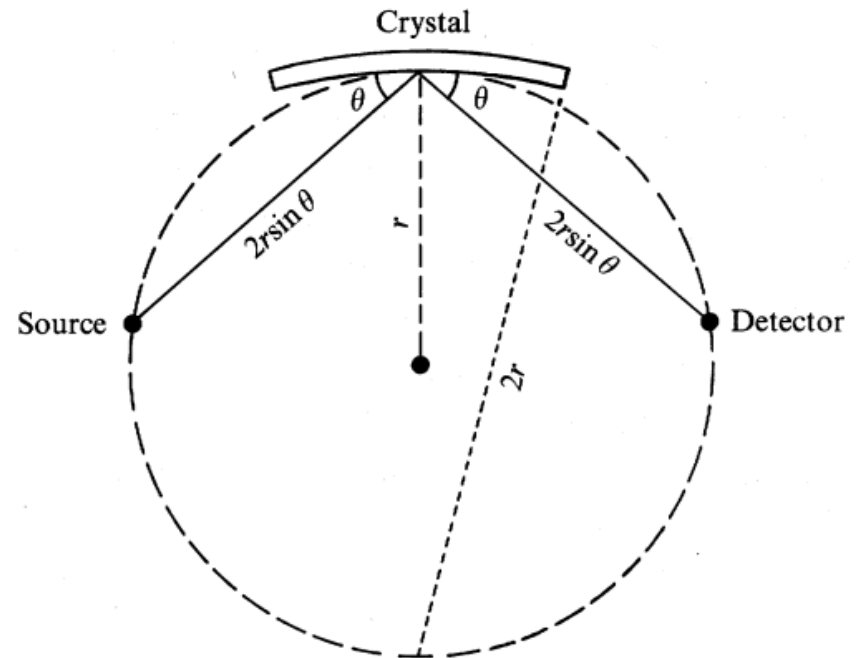
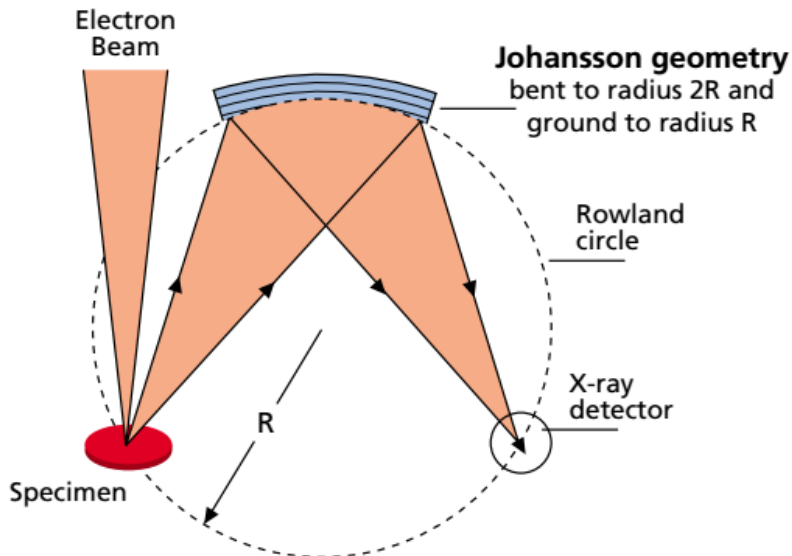
$E$  - the energy of the radiation

$F$  is the frequency of the radiation

$c$  is the speed of light

$\lambda$  is the wavelength of the radiation

$h$  is Planck's constant



Variation of  $\lambda$  by variation of  $\theta$  and  $d$

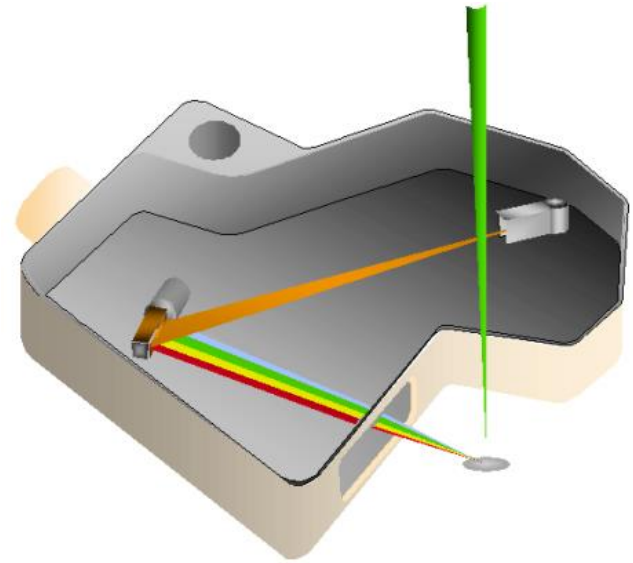
# Crystals for WDS



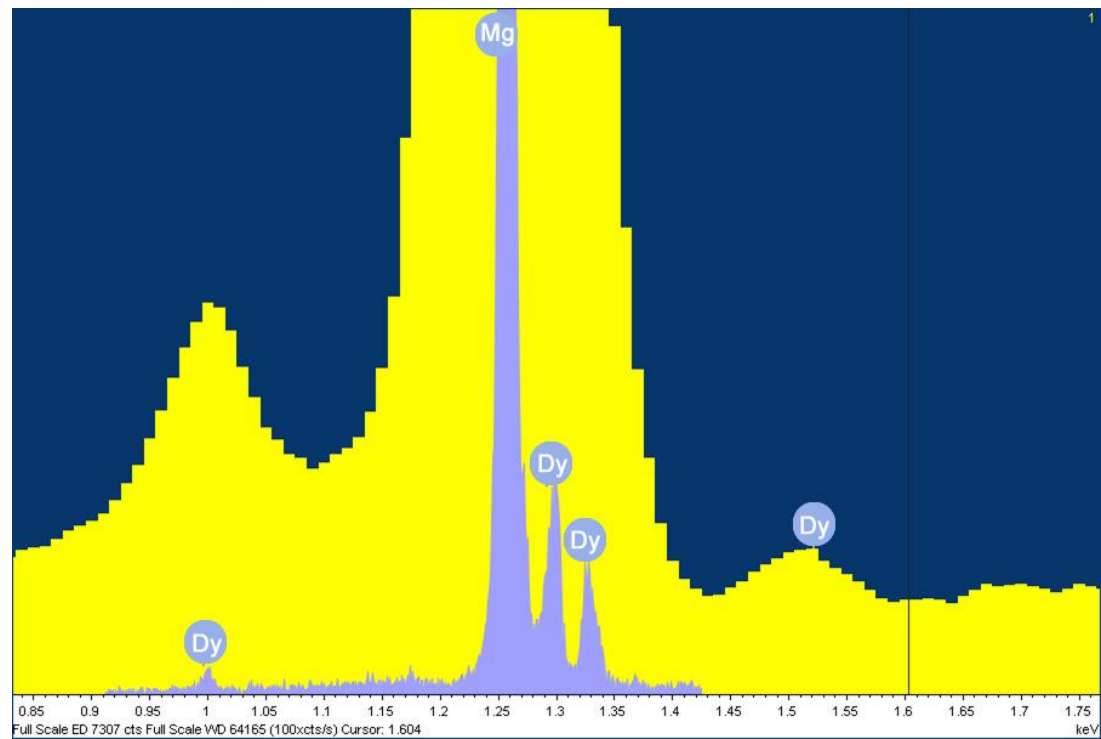
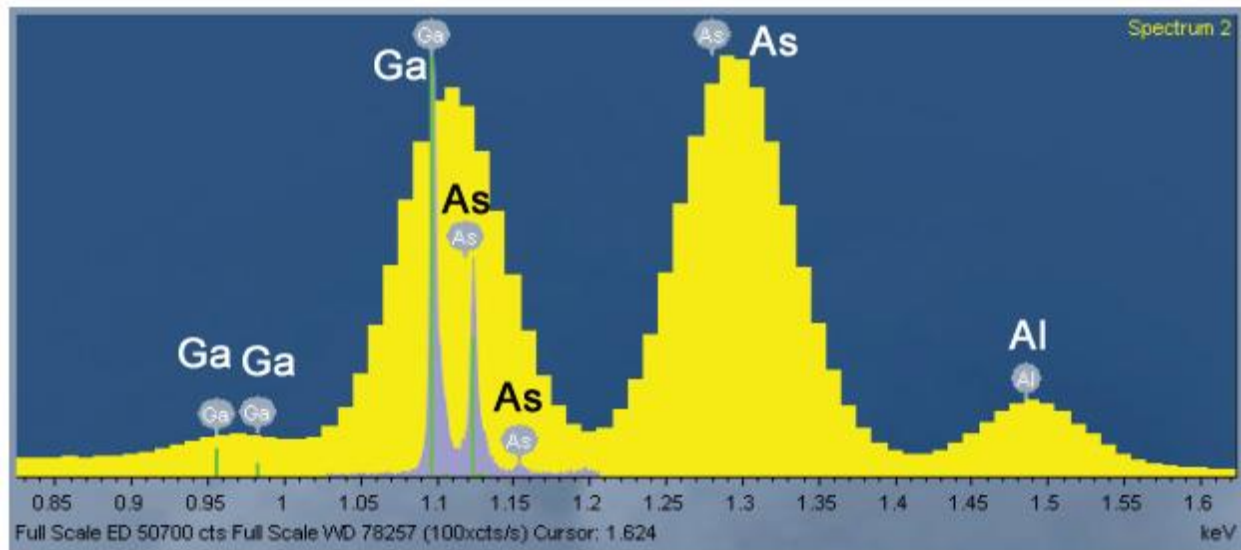
Table of guaranteed specifications for all crystals

<i>crystal</i>	<i>spectral line</i>	<i>wavelength nm</i>	<i>elemental standard</i>	<i>kV, detector type</i>	<i>resolution eV *</i>	<i>peak intensity cps/μA</i>	<i>p/b</i>	<i>sensitivity ppm</i>
<b>LSM-200</b>	Be Kα	11.4	Be	10, FPC	8	2.4 x 10 <sup>4</sup>	40	335
<b>LSM-200</b>	B Kα	6.76	B	10, FPC	15	9.0 x 10 <sup>5</sup>	30	63
<b>LSM-80N</b>	B Kα	6.76	B	10, FPC	9	5.7 x 10 <sup>4</sup>	60	180
<b>LSM-80N</b>	C Kα	4.47	Vitreous C	10, FPC	14	4.7 x 10 <sup>5</sup>	50	68
<b>LSM-80N</b>	N Kα	3.16	BN	10, FPC	16	9.5 x 10 <sup>3</sup>	3	1950
<b>LSM-80N</b>	O Kα	2.36	SiO <sub>2</sub>	10, FPC	17	1.1 x 10 <sup>5</sup>	50	140
<b>LSM-80E</b>	C Kα	4.47	Vitreous C	10, FPC	14	1.3 x 10 <sup>5</sup>	57	120
<b>LSM-80E</b>	N Kα	3.16	BN	10, FPC	16	3.4 x 10 <sup>4</sup>	13	495
<b>LSM-60</b>	C Kα	4.47	Vitreous C	10, FPC	12	3.2 x 10 <sup>4</sup>	70	220
<b>LSM-60</b>	N Kα	3.16	BN	10, FPC	13	5.0 x 10 <sup>3</sup>	10	1500
<b>LSM-60</b>	O Kα	2.36	SiO <sub>2</sub>	10, FPC	15	1.0 x 10 <sup>5</sup>	65	130
<b>TAP</b>	O Kα	2.36	SiO <sub>2</sub>	10, FPC	3	5.4 x 10 <sup>3</sup>	350	240
<b>TAP</b>	Al Kα	0.834	Al	20, FPC	9	2.7 x 10 <sup>6</sup>	800	7
<b>PET</b>	Si Kα	0.7126	Si	20, FPC	2	5.4 x 10 <sup>5</sup>	2600	9
<b>PET</b>	Ti Kα	0.2750	Ti	30, FPC/SPC	20	2.7 x 10 <sup>6</sup>	500	9
<b>LiF(200)</b>	Fe Kα	0.1937	Fe	30, FPC/SPC	25	1.0 x 10 <sup>6</sup>	525	15
<b>LiF(200)</b>	Cu Kα	0.1542	Cu	30, FPC/SPC	40	1.1 x 10 <sup>6</sup>	315	18
<b>LiF(220)</b>	Cu Kα	0.1542	Cu	30, FPC/SPC	35	3.0 x 10 <sup>5</sup>	400	30
<b>LiF(220)</b>	Ge Kα	0.1255	Ge	30, FPC/SPC	48	3.7 x 10 <sup>5</sup>	210	37

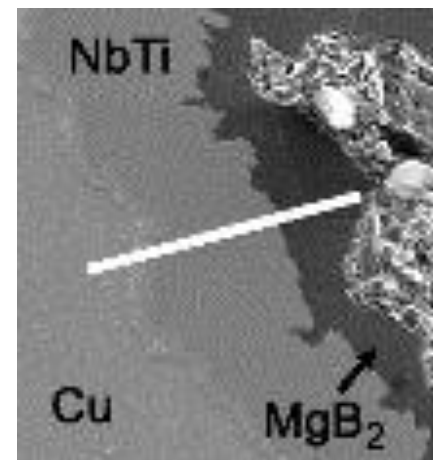
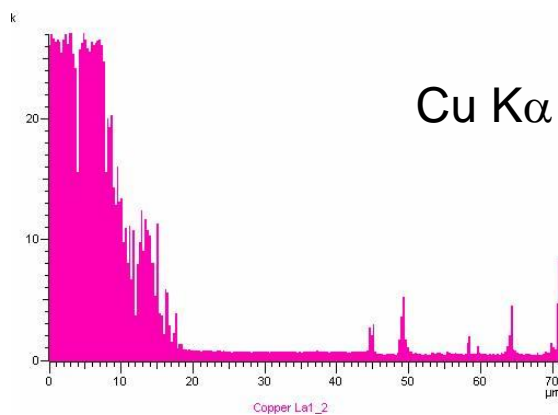
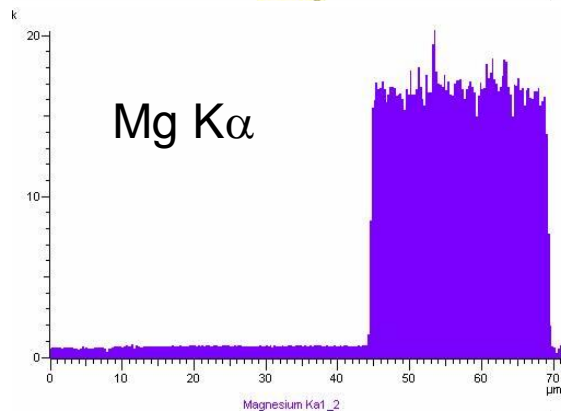
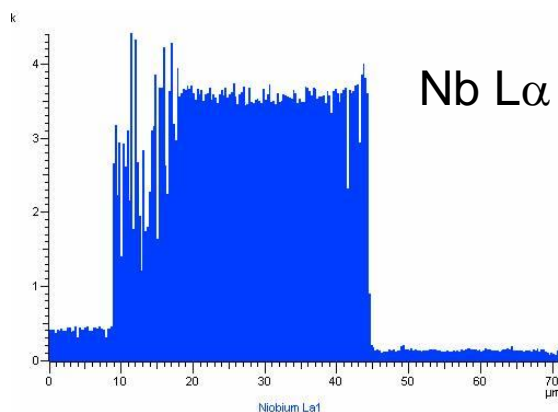
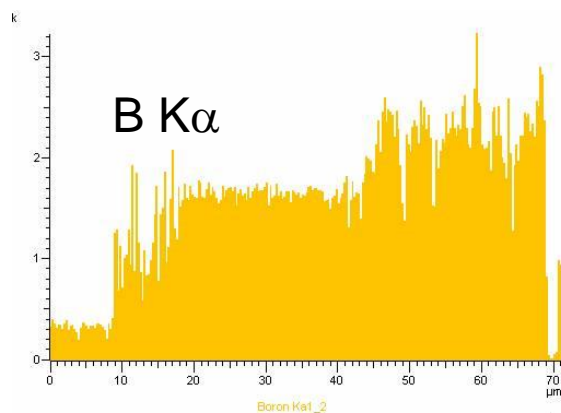
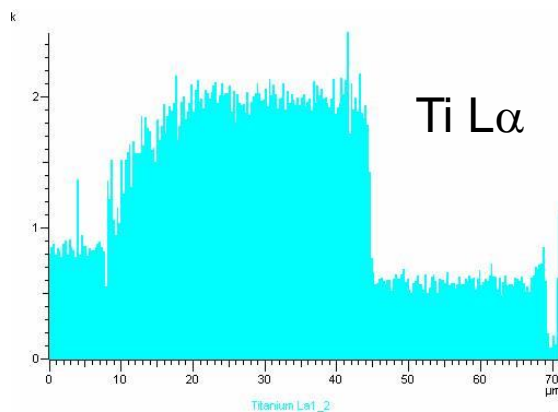
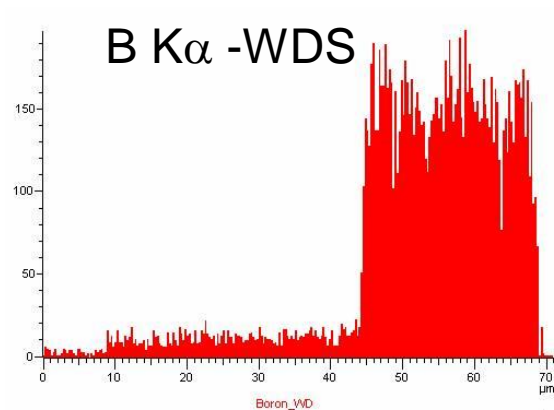
# WDS

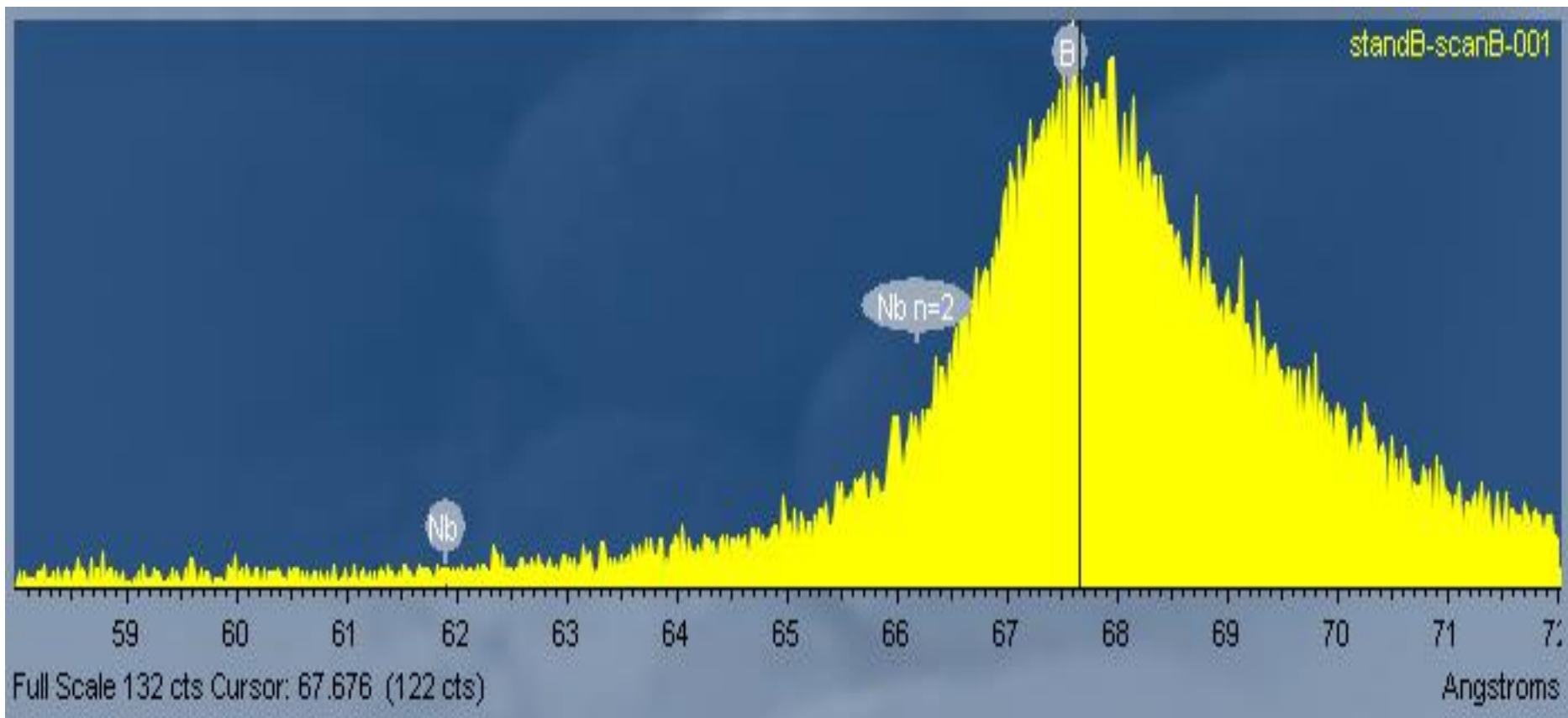


- detects only one energy X-rays in the time
- different signal detection – gas proportional counter
- high energy resolution 2 – 40 eV – **peak separation!!**
- high count rate capability without compromising energy resolution
- **Need of standards for every measured element !!!!!**
- time consuming, more complicated
- it has significantly better sensitivity of **100 – 10 ppm**

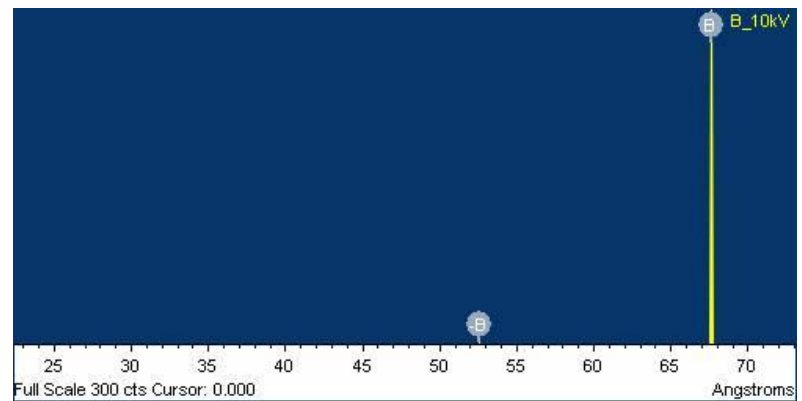
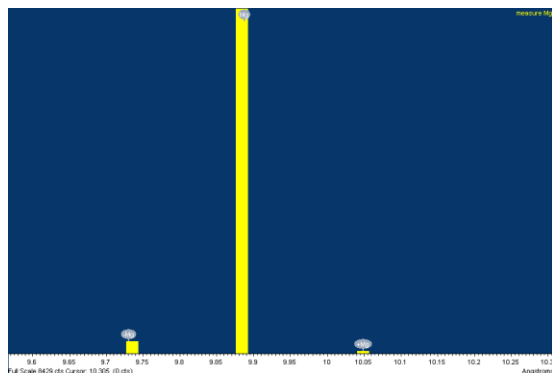


# MgB<sub>2</sub>/NbTi/Cu

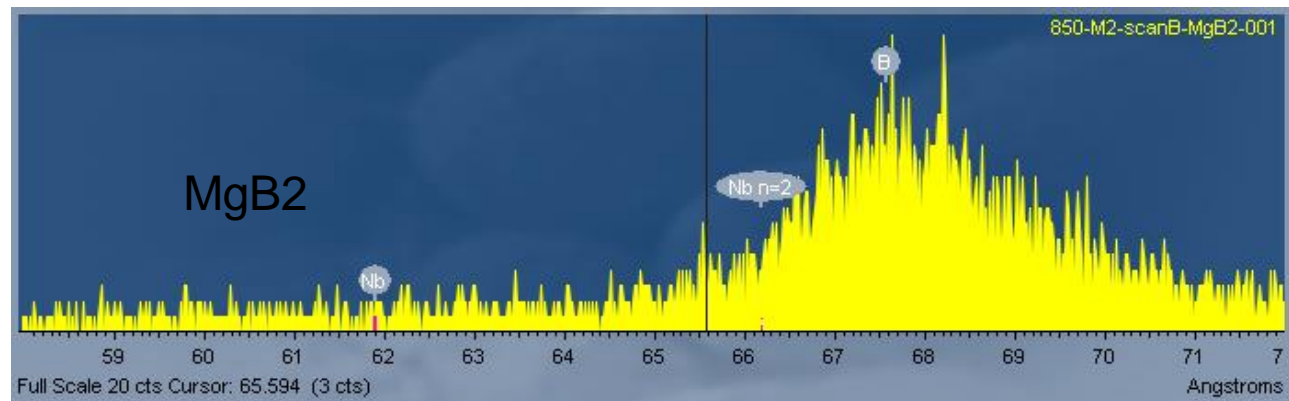
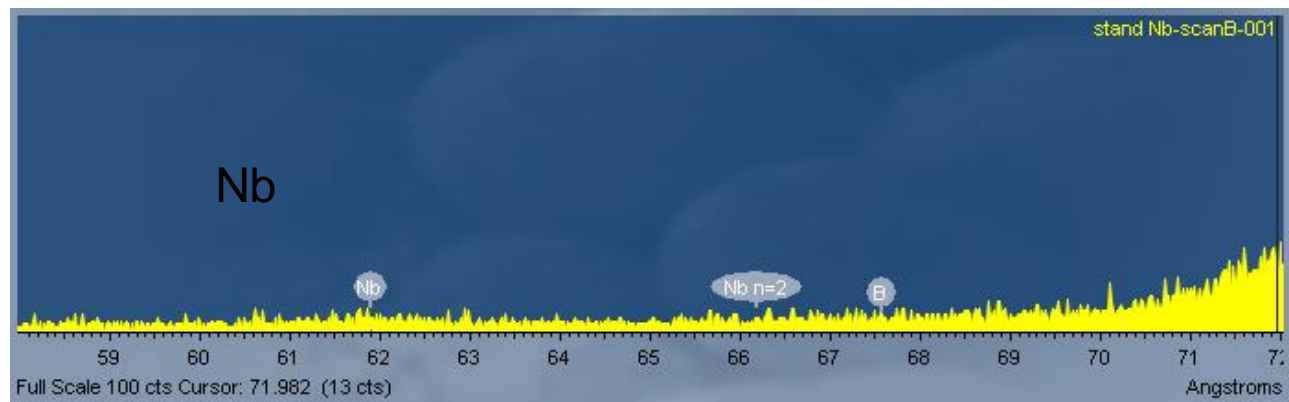
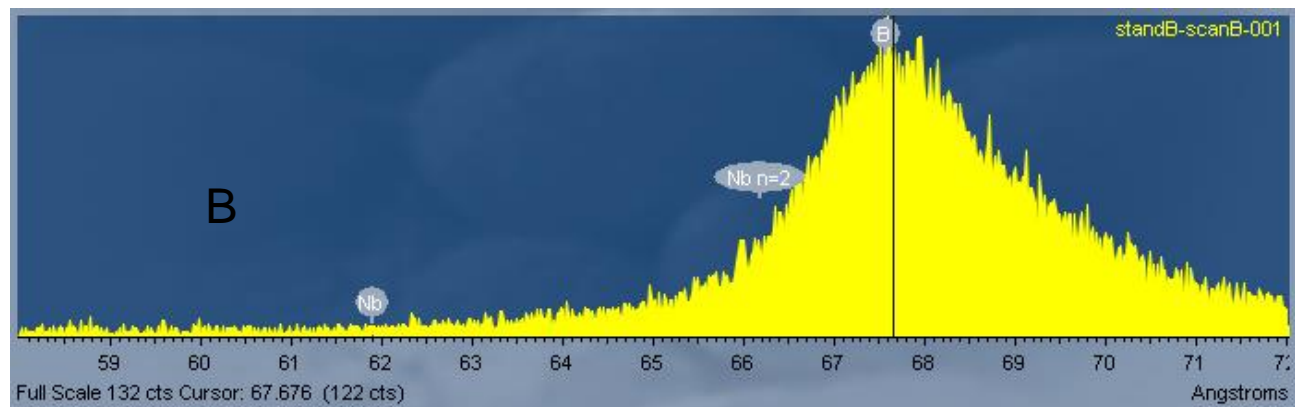




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# EDS X WDS

## EDS

- Complete spectrum of energies is acquired – and stored - simultaneously
- Complete spectra are stored – appropriate for later re-calculation or an element searching without measurement
- Low energy resolution – some combination of elements are difficult to recognize (Mo-S, Nb-B, ...)
- Data collection quick and analysis relatively simple – ideal for qualitative and rapid quantitative analysis
- Sensitivity – several tenths of wt% - **several 1000 ppm**

## WDS

- High energy resolution
- Ability to deal with higher count rates
- Sensitivity – typically of one to two order of magnitude lower concentration (**100 – 10 ppm**) – appropriate for trace analysis
- More complicated to set up, measure and more tedious to obtain results
- More expensive

Thank you for your attention

Any questions?